

Tuesday, October 25

Room A (2F)

25P-1: Plenary Session

Chairpersons: T. Meguro (Tokyo Univ. of Sci.) and M. Nagase (Univ. of Tokushima)

9:30-9:50

Opening Remark: H. Yamaguchi (NTT)

Award Presentation: Y. Miyamoto (Tokyo Inst. of Technol.) and H. Yamaguchi (NTT)

MNC 2010 Outstanding Paper, Most Impressive Presentation, Most Impressive Poster and Young Author's Award

Announcement from Committee: T. Itani (EIDEC) and T. Meguro (Tokyo Univ. of Sci.)

25P-1-1

9:50-10:30

Solving Energy and Environmental Problems (Plenary)

S. Wasaka, NEDO, Japan

Room P (2F)

Coffee Break

Room A (2F)

25P-1-2

10:50-11:30

Toward the Achievement of Ultra-Low Power Systems by taking advantages of BEOL Devices (Plenary)

N. Sumihiro, LEAP, Japan

25P-1-3

11:30-12:10

Chemistry of Graphene (Plenary)

L.K. Ping, Natl. Univ. of Singapore, Singapore

LUNCH

Room A (2F)

Room B (2F)

Room C (2F)

25A-2: Symp. A: Graphene I

Chairpersons:

K. Maehashi (Osaka Univ.)

M. Nagashio (Univ. of Tokyo)

25B-2: Microsystem Technology and MEMS I

Chairpersons:

N. Miki (Keio Univ.)

T. Ando (Ritsumeikan Univ.)

25C-2: BioMEMS, Lab on a Chip I

Chairpersons:

Y. Murakami (Hiroshima Univ.)

T. Matsumoto (Tokyo Medical and Dental Univ.)

25A-2-1

13:40

Graphene-metal Contacts: Influence of Graphene Layer Orientation and Thickness (Invited)

S. Kodambaka 1, Y. Murata 1, A. Ebnonnasir 2, E. Starodub 3, B.B. Kappes 2, S. Nie 3, N.C. Bartelt 3, K.F. McCarty 3 and C.V. Ciobanu 2, 1 UCLA, 2 Colorado School of Mines and 3 Sandia Natl. Labs., USA

25B-2-1

13:40

Vibration MEMS Power Generator using Polymer Electrets for Energy Harvesting Application (Invited)

Y. Suzuki, Univ. of Tokyo, Japan

25C-2-1

14:00

Microfluidic Assembly with Molecules and Cells (Invited)

S. Takeuchi, Univ. of Tokyo and JST-ERATO, Japan

25A-2-2

14:10

Synthesis of a Novel Carbon Structure: Multi-layer Graphene formed at the Both Sides of Catalyst Film on a Substrate

D. Kondo 1,2, S. Sato 1,2, K. Yagi 2, M. Nihei 1,2 and N. Yokoyama 1,2, 1 Fujitsu Labs and 2 AIST, Japan

25B-2-2

14:10

Thermal-photovoltaic Hybrid Solar Generator using Thin-film Thermoelectric Modules

M. Mizoshiri, M. Mikami and K. Ozaki, AIST, Japan

25C-2-2

14:30

Quasi-in vivo Heart Electrocardiogram Measurement using Convolution of Field Potential Propagation in Cardiomyocytes Network Circuit

F. Nomura, T. Kaneko and K. Yasuda, Tokyo Medical and Dental Univ., Japan

25A-2-3

14:30

Formation of Graphene on Diamond (111) Surfaces

N. Tokuda 1,2,3, M. Fukui 1, K. Kojima 4, K. Komatsu 4, K. Funatsu 4, T. Makino 2,3, D. Takeuchi 2,3, S. Yamasaki 2,3 and T. Inokuma 1, 1 Kanazawa Univ., 2 AIST, 3 JST-CREST and 4 MST, Japan

25B-2-3

14:30

A Venturi-type Micro Mist Generator fabricated by MEMS Technology and its Application to Local Surface Cooling of Target Objects

M. Arai, K. Terao, F. Shimokawa, T. Suzuki, F. Oohira and H. Takao, Kagawa Univ., Japan

25C-2-3

14:50

Immobilization and Observation of Exosomes in Microfluidic Device

M. Sasaki, T. Akagi and T. Ichiki, Univ. of Tokyo, Japan

25A-2-4

14:50

Tuning of Electronic Properties of Epitaxial Graphene on Microfabrication

H. Fukidome 1, H. Handa 1, M. Kotsugi 2,3, T. Seyller 4, Y. Kawai 1, T. Ohkouchi 2, K. Horn 5, R. Takahashi 1, K. Imaizumi 1, Y. Enta 6, M. Suemitsu 1 and T. Kinoshita 2,3, 1 Tohoku Univ., 2 JASRI-SPring8, 3 JST-CREST, Japan, 4 Friedrich-Alexander-Univ. 5 Max-Planck-Gesellschaft, Germany and 6 Hirosaki Univ., Japan

25B-2-4

14:50

Demonstration of Vibrational Braille Code Display using Large Displacement MEMS Actuators

J. Watanabe 1, H. Ishikawa 1, X. Arouette 1, Y. Matsumoto 1 and N. Miki 1,2, 1 Keio Univ. and 2 JST-PRESTO, Japan

25C-2-4

15:10

Simultaneous Filtration and Focusing of Cancerous Cells in an Insulator-based Dielectrophoretic Microchip

W.-F. Chen and C.-P. Jen, Natl. Chung Cheng Univ., Taiwan

25A-2-5

15:10

Characteristics of the Field Effect Transistor using Graphene Layers grown on Graphene Template by Chemical Vapor Deposition

R. Negishi, Y. Ohno, K. Maehashi, K. Matsumoto and Y. Kobayashi, Osaka Univ., Japan

25B-2-5

15:10

A Miniaturized Dual-axis Electrolytic Tilt Sensor

J.C. Choi 1, Y.C. Choi 1, W.-J. Kim 2 and S.H. Kong 1, 1 Kyungpook Natl. Univ. and 2 MENTech., Korea

25C-2-5

15:30

Airborne Virus Micro-hole Sampler designed by Particle Track Analysis for the Pandemic Prevention

K. Takenaka, Y. Sasaki and S. Togashi, Hitachi, Japan

	25B-2-6 15:30 A MEMS-based Micro Ro-boat using Water Steam Y.C. Choi, J.C. Choi and S.H. Kong, Kyungpook Natl. Univ., Korea	
Room P (2F)		
Coffee Break		
Room A (2F)	Room B (2F)	Room C (2F)
25A-3: Symp. A: Graphene II Chairpersons: D. Kondo (Fujitsu Labs.) K. Hirahara (Osaka Univ.)	25B-3: Microsystem Technology and MEMS II Chairpersons: H. Takao (Kagawa Univ.) Y.-C. Lin (Tohoku Univ.)	25C-3: BioMEMS, Lab on a Chip II Chairpersons: Y. Takamura (JAIST) T. Ichiki (Univ. of Tokyo)
25A-3-1 15:50 Graphene as an Emerging Material for Future Electronics (Invited) X. Duan, UCLA, USA	25B-3-1 16:05 MEMS Resonator: What is the challenge? (Invited) K. Suzuki, Ritsumeikan Univ., Japan	25C-3-1 16:10 Effect of Microscale Surface Geometry of Electrodes on Performance of Microbial Fuel Cells T. Kano 1, E. Suito 1 and N. Miki 1,2, 1 Keio Univ. and 2 NEDO BEANS Project, Japan
25A-3-2 16:20 Graphene: Production Strategies, Characterization and Applications (Invited) F. Bonaccorso and A.C. Ferrari, Univ. of Cambridge, UK	25B-3-2 16:35 High Q-factor 80 MHz MEMS Resonator utilizing Torsional-to-transverse Vibration Conversion M. Kiso 1, M. Okada 1, H. Fujiura 1, H. Miyauchi 1, K. Niki 1, H. Tanigawa 2 and K. Suzuki 2, 1 Sanyo Electric and 2 Ritsumeikan Univ., Japan	25C-3-2 16:30 Microfluidic Design of Catalytic Packed-bed Multi-channel Reactor for Gas-liquid Multiphase Reaction S. Murakami, K. Ohtaki, S. Matsumoto and T. Inoue, AIST, Japan
25A-3-3 16:50 Evaluation of Graphene Thin Films by Surface Plasmon Resonance K. Murasaki, S. Akita and T. Arie, Osaka Pref. Univ., Japan	25B-3-3 16:55 Frequency Stability of MEMS Oscillators: Material Property Effect and Circuit Phase Effect T. Ikehara 1, M. Konno 1, S. Murakami 1 and T. Mihara 2, 1 AIST and 2 Olympus, Japan	25C-3-3 16:50 Microfluidic Chip-based Organophosphorus Detection using Bienzyme Bioelectrocatalysis C.Y. Jeong 1, Y.D. Han 1, D.S. Lee 2 and H.C. Yoon 1, 1 Ajou Univ. and 2 Electronics Telecommunications Res. Inst., Korea
25A-3-4 17:10 Immunosensors based on Graphene Field-effect Transistors using Antigen-binding Fragments S. Okamoto, Y. Ohno, K. Maehashi, K. Inoue and K. Matsumoto, Osaka Univ., Japan	25B-3-4 17:15 Reliability of Organic Membrane Structure embedded in Silicon-interposer Chip M. Taketomo, S. Mitarai, K. Oniki and K. Ikeda, Sony, Japan	25C-2, 3 Author's Interview: 17:10-17:20
	25B-3-5 17:35 Variable Gap Silicon Waveguide Directional Coupler Switch Y. Akihama, Y. Kanamori and K. Hane, Tohoku Univ., Japan	
25A-2,3 Author's Interview: 17:30-17:40	25B-2, 3 Author's Interview: 17:55-18:05	

Wednesday, October 26

Room A (2F)	Room B (2F)	Room C (2F)
26A-4: Nano Carbon I Chairpersons: J. Fujita (Univ. of Tsukuba) M. Tanemura (Nagoya Inst. of Technol.)	26B-4: Symp. B: Molecular Modification /molecular Self -assembly for Micro/nano-structure Chairpersons: Y. Ono (NTT) A. Kohno (Fukuoka Univ.)	26C-4: Novel Transistors Chairpersons: N. Banno (Leap) K. Nishiguchi (NTT)
26A-4-1 9:00 Complementary in-situ probing of Graphene and Carbon Nanotube CVD (Invited) S. Hofmann, Univ. of Cambridge, UK	26B-4-1 9:00 Au Nanoparticle Single-Electron Transistors on Electroless Gold-Plated Nanogap Electrodes (Invited) Y. Majima, Tokyo Inst. of Technol., Japan	26C-4-1 9:00 Atom Movement Controlled Three-terminal Device, 'Atom Transistor' (Invited) T. Hasegawa, NIMS and JST-CREST, Japan
26A-4-2 9:30 CVD Gas Pressure Dependence of Horizontally Aligned Single-walled Carbon Nanotubes grown on R-cut Crystal Quartz Substrates T. Inoue, D. Hasegawa, S. Badar, S. Chiashi, J. Shiomi and S. Maruyama, Univ. of Tokyo, Japan	26B-4-2 9:30 Self-assembled Molecular Nanowires for Multi-channel Transistor (Invited) Y. Wakayama, NIMS, Japan	26C-4-2 9:30 Fabrication of Vertical $\text{In}_{0.7}\text{Ga}_{0.3}\text{As}$ Nanowire Surrounding-gate Transistors with High- k Gate Dielectric on Si Substrate K. Tomioka 1, 2M. Yoshimura 1 and T. Fukui 1, 1 Hokkaido Univ. and 2 JST-PRESTO, Japan
26A-4-3 9:50 In-situ Observation of Current-pulse-induced Fullerene Production T. Nishijima 1,2, R. Ueki 1,2, E. Kano 1,2 and J. Fujita 1,2, 1 Tsukuba Res. Ctr. for Interdisciplinary Materials Sci. and 2 Univ. of Tsukuba, Japan	26B-4-3 10:10 Overview of Directed Self-Assembly / Basic and application (Invited) M. Muramatsu, Tokyo Electron Kyushu, Japan	26C-4-3 9:50 Fabrication and Characterization of InAs Nanowire Vertical Surrounding-gate FETs Y. Kobayashi, Y. Kohashi, S. Hara and J. Motohisa, Hokkaido Univ., Japan
26A-4-4 10:10 Characterization of Carbon Nanotubes by Atomically Resolved Electron-diffraction Microscope T. Dobashi 1, Y. Maehara 2, K. Gohara 2 and O. Kamimura 1, 1 Hitachi and 2 Hokkaido Univ., Japan	26B-4-4 10:40 Directed Self-Assembly of Block Copolymers toward Single-Digit Nanolithography (Invited) T. Yamaguchi 1,2*, H. Yamaguchi 1, T. Iyoda 2, 1 NTT and 2 Tokyo Inst. of Technol., Japan	26C-4-4 10:10 Low-frequency Noise in GaAs Nanowire MISFETs having SiN_x Gate Insulator T. Muramatsu, K. Miura, Y. Shiratori and S. Kasai, Hokkaido Univ., Japan
26A-4-5 10:30 Recovery Force of Carbon Nanotube Shape Memory S. Itaya, K. Hirahara and Y. Nakayama, Osaka Univ., Japan	26B-4 Author's Interview: 11:10-11:20	26C-4-5L 10:30 L-Shaped Tunneling Field-Effect Transistors (TFETs) for Low Subthreshold Swing and High Current Drivability S.W. Kim 1, W.Y. Choi 2, M.-C.Sun 1, H.W. Kim 1, J.-H. Lee 1, H. Shin 1 and B.-G. Park 1, 1 Seoul Nat. Univ. and 2 Sogang Univ., Korea
		26C-4-6 10:50 Characteristics of Gate-all-around Hetero-gate-dielectric Tunneling FETs J.S. Lee 1, W.Y. Choi 2 and I.M. Kang 1, 1 Kyungpook Natl. Univ. and 2 Sogang Univ., Korea
Room P (2F)		
Coffee Break		
Room A (2F)	Room B (2F)	Room C (2F)
26A-5: Nano Carbon I Chairpersons: T. Takenobu (Waseda Univ.) S. Okada (Univ. of Tsukuba)	26B-5: Nanomaterials I Chairpersons: J. Kawakita (NIMS)	26C-5: New Functional Devices Chairpersons: N. Banno (Leap) K. Nishiguchi (NTT)
26A-5-1 11:05 Electric Field Enhancement by Laser Light focused on Electrode Edges for Controlled-positioning of Carbon Nanotubes T. Takahashi, R. Inori, T. Okada, T. Arie and S. Akita, Osaka Pref. Univ., Japan	26B-5-1 11:25 Single-Electron Tunneling via Molecular Quantum Dots Embedded in a Metal-Insulator-Semiconductor Structure (Invited) R. Hayakawa 1, N. Hiroshiba 2, T. Chikyo 1 and Y. Wakayama 1, 1 NIMS and 2 Univ. of Tsukuba, Japan	26C-5-1 11:25 Ag_2S Synaptic Device showing Short and Long Term Memory T. Ohno 1, T. Hasegawa 1, T. Tsuruoka 1, K. Terabe 1, J.K. Gimzewski 1,2 and M. Aono 1, 1 NIMS, Japan and 2 UCLA, USA

<p>26A-5-2 11:25 Single-welled Carbon Nanotube Transistors using Ion-gel Y. Yomogida 1, T. Takenobu 2, D. Wen 2, H. Shimotani 1, K. Yanagi 3 and Y. Iwasa 4, 1 Tohoku Univ., 2 Waseda Univ., 3 Tokyo Metropolitan Univ. and 4 Univ. of Tokyo, Japan</p>	<p>26B-5-2 11:55 Dielectric and Surface Morphology Properties of PVDF-TrFe/PMMA:TiO₂ Multilayer Dielectric Thin Films for Organic Field Effect Transistors Application L.N. Ismail, M.H.M. Wahid, Z. Habibah, S.H. Herman and M. Rusop, Univ. Teknologi MARA, Malaysia</p>	<p>26C-5-2 11:45 Proposal of 1-Diode Type Resistive Switching Memory using Cr-doped SrTiO₃ M.Y. Song, Y. Seo, Y.S. Kim, J.H. Jeon, H.-D. Kim, H.-M. An, K.-H. Kim and T.G. Kim, Korea Univ., Korea</p>
<p>26A-5-3 11:45 Carbon Nanotube-based Floating Gate Memory with High-k Dielectrics Y. Fujii, T. Ohori, Y. Ohno, K. Maehashi, K. Inoue and K. Matsumoto, Osaka Univ., Japan</p>	<p>26B-5-3 12:15 Ternary PbSSe Nanocrystal:poly(3-hexylthiophene) Nanocomposites for Near Infrared-sensitive Hybrid Solar Cells M. Nam, S. Kim, S.-W. Kim and K.-K. Lee, Ajou Univ., Korea</p>	<p>26C-5-3 12:05 Color Filter using Dielectric Multilayer and Guided Mode Resonant Grating for CMOS Image Sensor Y. Konno, K. Shiozawa, K. Kokubun, T. Yorisaki, J. Tonotani, N. Momo, H. Sasaki, H.S. Momose, T. Ohguro and N. Okada, Toshiba, Japan</p>
<p>26A-5-4 12:05 Extremely Flexible All-carbon Nanotube Field-effect Transistors without Device Degradation S. Aikawa 1,2, E. Einarsson 1, S. Chiashi 1, E. Nishikawa 2 and S. Maruyama 1, 1 Univ. of Tokyo and 2 Tokyo Univ. of Sci., Japan</p>		
26A-4, 5 Author's Interview: 12:25-12:35		26C-4, 5 Author's Interview: 12:25-12:35
LUNCH		
Room A (2F)	Room B (2F)	Room C (2F)
<p>26A-6: Lithography and Metrology Chairpersons: T. Sato (Toshiba) H. Yamashita (HOYA)</p>	<p>26B-6: Nanomaterials II Chairpersons: T. Ishida (AIST)</p>	<p>26C-6: New Conceptual Devices Chairpersons: S. Kasai (Hokkaido Univ.) H. Ikeda (Shizuoka Univ.)</p>
<p>26A-6-1 14:00 Contribution of Optical Lithography to Development of Optical Designing Theory (<i>Invited</i>) M. Shibuya, Tokyo Polytechnic Univ., Japan</p>	<p>26B-6-1 14:00 Interfacial Reactions of Nickel Metal Nanodots on Single-crystal (001)Si_{1-x}C_x Substrates S.L. Cheng, Y.C. Tseng and S.W. Lee, Natl. Cent. Univ., Taiwan</p>	<p>26C-6-1 14:00 Minimum Energy for Computation and the Landauer Principle (<i>Invited</i>) G. Snider, Univ. of Notre Dame, USA</p>
<p>26A-6-2 14:30 EUV Lithography: NXE:3100 delivered to Fabs and building of NXE:3300B has started R. Peeters, S. Young, H. Meiling, N. Hamed, R. Droste, J. Stoeldraaijer, H. Meijer and R. Kool, ASML Netherlands, Netherlands</p>	<p>26B-6-2 14:20 Fast Formation of Conductive Material by Simultaneous Chemical Process for Infilling TSV J. Kawakita and T. Chikyow, NIMS, Japan</p>	<p>26C-6-2 14:30 Fabrication of Functional Oxide Nanostructures and the Electronic Application utilizing Stochastic Resonance T. Kanki, H. Takami, K. Kawatani and H. Tanaka, Osaka Univ., Japan</p>
<p>26A-6-3 14:50 Characterization of Anode-shockwave and Plasma Diffusion in a Laser Assisted Discharge Produced Plasma 13.5 nm EUV Source for Lithography Q. Zhu, T. Muto, J. Yamada, N. Kishi, M. Watanabe, A. Okino, K. Horioka and E. Hotta, Tokyo Inst. of Technol., Japan</p>	<p>26B-6-3 14:40 Properties of Nitrogen-atom Endohedral Fullerene efficiently synthesized using Controlled Radio-frequency Discharge Plasma S.C. Cho, T. Kaneko and R. Hatakeyama, Tohoku Univ., Japan</p>	<p>26C-6-3 14:50 Noise-induced Stochastic Enhancement for a Device based on Redox-active Huge Molecule and DNA Nanonetwork T. Matsumoto, Y. Hirano, Y. Segawa, and T. Kawai, Osaka Univ., Japan</p>
<p>26A-6-4 15:10 2D and 3D Resist Line Roughness Characterization A.V. Pret 1,2, E. Kunnen 1, R. Gronheid 1, E. Pargon 3, O. Luere3 and D. Bianchi 4, 1 IMEC, 2 K.U.Leuven, Belgium, 3 CNRS-LTM, France and 4 AC²T res. Austria</p>	<p>26B-6-4 15:00 Fabrication of Metal Thin Film Patterns on Hydro-gels N. Shimamoto 1,2, H. Mitomo 1,2, R. Kawamura 1, K. Kawabata 1, R. Kishi 3, K. Sano 1,4, K. Ijro 1,2 and Y. Osada 1, 1 RIKEN, 2 Hokkaido Univ., 3 AIST and 4 Nippon Inst. Technol., Japan</p>	<p>26C-6-4 15:10 Stochastic Resonance using a Steep-subthreshold-swing Transistor K. Nishiguchi and A. Fujiwara, NTT, Japan</p>
<p>26A-6-5 15:30 Photoresist Shrinkage caused by Single-line Scan of Electron Beam T. Ohashi and J. Tanaka, Hitachi, Japan</p>	<p>26B-6-5 15:20 Driving Water Droplets on Superhydrophobic-hydrophilic Patterned Si Nanowire Surface S. Lee, J. Seo and T. Lee, Yonsei Univ., Korea</p>	<p>26C-6-5L 15:30 Single-Photon Detection by a Simple SOI MOSFET W. Du, H. Inokawa and H. Satoh, Shizuoka Univ., Japan</p>
26A-6 Author's Interview: 15:50-16:00	26B-5, 6 Author's Interview: 15:40-15:50	26C-6 Author's Interview: 15:50-16:00

Room P (2F)

Coffee Break

26P-7: 16:00-18:00 POSTER SESSION I

Lithography and Metrology

<p>26P-7-1 GPU-based High Speed Algorithms for Photomask Layout Verification and Application Study on 2Xnm SRAM K. Kadota 1, K. Kato 2 and T. Inoue 2, 1 AIST and 2 SII Nano Technol., Japan</p>	<p>26P-7-2 Micro Coherent EUV Scatterometry Microscope for a Defect Characterization on an EUV Mask T. Harada 1, M. Nakasuji 1, A. Tokimasa 1, T. Watanabe 1, Y. Usui 2 and H. Kinoshita 1, 1 Univ. of Hyogo and 2 EIDEC, Japan</p>	<p>26P-7-3 Micro Patterning on Nonplanar Substrates using Unconventional Photolithographic Technique with Flexible Photomask J. Park, H. Fujita and B. Kim, Univ. of Tokyo, Japan</p>
<p>26P-7-4 Optical Metrology of Shape-varying Nano-patterned Gratings by analyzing the Scattering Signals in their Pupil Images Y.M. Lee 1, J.H. Li 1, F.M. Wang 1, H.H. Cheng 1, Y.T. Shen 1, K.Y. Tsai 1 and A.C. Chen 2, 1 Natl. Taiwan Univ. and 2 ASML, Taiwan</p>	<p>26P-7-5 The Effect on CD Performance for Carbon Contamination of EUV Mask using Coherent Scattering Microscopy / In-situ Contamination System J. Doh 1,2, S. Lee 1, J. Lee 1, S. Hong 1, I. Lee 1, S. Park 1, C.Y. Jeong 2, D.G. Lee 2, S.-S. Kim 2, H.-K. Cho 2 and J. Ahn 1, 1 Hanyang Univ. and 2 Samsung Electronics, Korea</p>	<p>26P-7-6 Defect Inspection Technique using Surface Plasmon Resonance H. Kashiwagi, I. Yoneda, K. Morishita, R. Yoshikawa, T. Hirano and T. Nakasugi, Toshiba, Japan</p>
<p>26P-7-7 EUV Process Optimization for Contact Layer of 14nm Node Logic and 16nm Half Pitch Memory Devices S.-E. Tseng and A. Chen, ASML, Taiwan</p>	<p>26P-7-8 An Optimized Multi-grid Strategy for Accurate Flare Modeling with 3D Mask Effect in EUV Lithography J. Lee 1, S. Lee 1, C. Kim 2, Y. Kim 2, S. Kim 2 and O. Kim 1, 1 POSTECH and 2 Hynix Semiconductor, Korea</p>	<p>26P-7-9 Volume Production LLP EUV Sources J. Bonafede, Cymer Japan, Japan</p>
<p>26P-7-10 Maskless Lithographic Fine-patterning onto Deep or Slope Surface using a Newly Developed DMD Exposure Equipment W. Iwasaki 1, Y. Peng 1, T. Takeshita 1, H. Shibata 2, Y. Kudo 2, R. Maeda 3 and R. Sawada 1, 1 Kyushu Univ., 2 Nikon and 3 AIST, Japan</p>	<p>26P-7-11 Cost Effective Lithography by Extension of Mask Aligner Lithography Techniques M. Homung 1, A. Erdmann 2, M. Hennemeyer 1, U. Hofmann 3, K. Motzek 2 and N. Ünal 3, 1 SUSS MicroTec Lithography, 2 Fraunhofer Inst. for Integrated Systems & Device Technol. and 3 GenlSys, Germany</p>	<p>26P-7-12 Simulation Analysis of Image Drift induced by Charging N. Okai and Y. Sohda, Hitachi, Japan</p>
<p>26P-7-13 Patterning of Spiral Structure on Optical Fiber by Focused-ion-beam Etching H. Mekaru 1 and T. Yano 2, 1 AIST and 2 Inst. for Molecular Sci., Japan</p>	<p>26P-7-14 Micro-IBIL Analysis as Diagnostic Tool for the Micro-structure Patterning on Diamond by Proton Beam Writing W. Kada 1, A. Yokoyama 1, M. Koka 1, K. Takano 2, T. Satoh 1 and T. Kamiya 1, 1 JAEA and 2 Osaka Univ., Japan</p>	<p>26P-7-15 EB Drawing of 15 nm × 15 nm Pitched Nanodot Arrays with a Size of < 10nm using High Contrast Developer T. Komori, H. Zhang, T. Akahane, Z. Mohamad, Y. Yin and S. Hosaka, Gunma Univ., Japan</p>
<p>26P-7-138L Development of Coherent EUV Scatterometry Microscope with High-order Harmonic Generation Source for EUV Mask Inspection and Metrology M. Nakasuji 1,3, A. Tokimasa 1,3, T. Harada 1,3, Y. Nagata 2,3, T. Watanabe 1,3, K. Midorikawa 2 and H. Kinoshita 1,3, 1 Univ of Hyogo, 2 RIKEN and 3 JST-CREST, Japan</p>	<p>26P-7-139L Measurement of Surface Potential Distribution of Resist Irradiated by Fogging Electrons A. Osada 1, M. Otani 2 Y. Ohara 2 and M. Kotera 1,2, 1 Osaka Inst. of Technol. and 2 Nanomaterials Microdevices Res. Ctr., Japan</p>	

Nanocarbons

<p>26P-7-16 Graphene/Cobalt Interface Structures in Cobalt-encapsulated Carbon Nanocapsules D. Matsuura and T. Kizuka, Univ. of Tsukuba, Japan</p>	<p>26P-7-17 Atomic Layer Deposition of Amorphous Carbon and Multilayer Graphene using Carbon Tetrabromide as Carbon Solid Source T. Choi, H. Kang, J. Yoon, H. Jung and H. Kim, Yonsei Univ., Korea</p>	<p>26P-7-18 Ni-particle as a Catalyst on Thermal Reduction of Graphene Oxide (GO): ReaxFF based on Molecular Dynamics Simulations Y. Hwang, K.-H. Yun, H. Choi and Y.-C. Chung, Hanyang Univ., Korea</p>
<p>26P-7-19 Electronic Structure of Graphene adsorbed on HfO₂ Surfaces K. Kamiya 1,2, N. Umezawa 3 and S. Okada 1,2, 1 Univ. of Tsukuba, 2 JST-CREST and 3 NIMS, Japan</p>	<p>26P-7-20 Effect of SiH₄ Pre-annealing on Graphitization of 3C-SiC/Si H. Fukidome 1, S. Abe 1, H. Handa 1, R. Takahashi 1, K. Imaizumi 1, S. Sanbonsuge 1 and M. Suemitsu 1,2, 1 Tohoku Univ. and 2 JST-CREST, Japan</p>	<p>26P-7-21 Preparation of Pd-decorated Graphene and Investigation of its Electrochemical Properties J.D. Kim and H.C. Choi, Chonnam Natl. Univ., Korea</p>
<p>26P-7-22 Improvement of Optical Graphene Layer Identification for Large-area Characterization S.F.A. Rahman 1,2, A.M. Hashim 1 and S. Kasai 2, 1 Univ. Teknologi Malaysia, Malaysia and 2 Hokkaido Univ., Japan</p>	<p>26P-7-23 The Observation of Chemical Reactions during Reduction of Graphene Oxide under bi-axial Strain: ReaxFF using Molecular Dynamics Simulations K.-H. Yun, Y. Hwang, H. Choi, D.S. Yoo and Y.-C. Chung, Hanyang Univ., Korea</p>	<p>26P-7-24 Process Optimization for Synthesis of High-quality Graphene Films by Low Pressure Chemical Vapor Deposition D. Lee, K. Lee, S. Jeong, J. Lee, B. Choi, J. Lee and O. Kim, POSTECH, Korea</p>
<p>26P-7-25 Amorphous Carbon Deposition by a Novel Aerosol-assisted CVD (AACVD) for Photovoltaic Solar Cell A.N. Fadzilah, K. Dayana and M. Rusop, Univ. Teknologi MARA, Malaysia</p>	<p>26P-7-26 Photophysical Properties of Aqueous Fullerene Nanoparticles prepared by Laser Ablation in Water T. Asahi 1, Y. Ishibashi 1, M. Arinishi 1 and H. Miyasaka 2, 1 Ehime Univ. and 2 Osaka Univ., Japan</p>	<p>26P-7-27 Multi-constituent co-assembly for Preparation of ZnO/Mesoporous Carbon Nanocomposite U.B. Suryavanshi, T. Iijima, A. Hayashi, Y. Hayashi and M. Tanemura, Nagoya Inst. of Technol., Japan</p>

<p>26P-7-28 The Growth Rate of Polycrystalline Diamond Films prepared by Hot-filament Chemical Vapor Deposition Methods H. Nagasaka, I. Nakamura, Y. Teranishi, T. Shimizu and T. Watanabe, Tokyo Metropolitan Industrial Technol. Res. Inst., Japan</p>	<p>26P-7-29 Inkjet Printing of CNT-TFTs patterned by Surface Modification Y. Nobusa 1, S. Matsuzaki 1, Y. Yomogida 2, K. Yanagi 3, H. Kataura 4 and T. Takenobu 1,5, 1 Waseda Univ., 2 Tohoku Univ., 3 Tokyo Metropolitan Univ., 4 JST-CREST and 5 JST-PREST, Japan</p>	<p>26P-7-30 Carbon Nanotube Inverter using Inkjet Method S. Matsuzaki 1, Y. Nobusa 1, K. Yanagi 2, H. Kataura 3 and T. Takenobu 1,3,4, 1 Waseda Univ., 2 Tokyo Metropolitan Univ., 3 JST-CREST and 4 JST-PRESTO, Japan</p>
<p>26P-7-31 One-step Liquid-phase Synthesis of Carbon Nanotubes: Effects of Substrate Materials on Morphology of Carbon Nanotubes K. Yamagiwa, Y. Ayato and J. Kuwano, Tokyo Univ. of Sci., Japan</p>	<p>26P-7-32 Fabrication of the Archimedean Spiral Patterned Capacitor using the Nanostructure of TiO₂ and Carbon Nanotubes J.-R. Huang, Y.-R. Huang, H.-C. Chang, C.-A. Chen, W.-J. Su, S.-L. Lee, Y.-S. Huang and K.-Y. Lee, Natl. Taiwan Univ. of Sci. & Technol., Taiwan</p>	<p>26P-7-33 Enhancing Separation Force in Brush-like Carbon Nanotubes by Gas Phase Oxidation A. Fallahgilvaei and Y. Nakayama, Osaka Univ., Japan</p>
<p>26P-7-34 Application of the Liquid-liquid Interfacial Precipitation Method to Synthesis of Co-encapsulated Carbon Nanocapsules D. Matsuura 1, K. Miyazawa 2 and T. Kizuka 1, 1 Univ. of Tsukuba and 2 NIMS, Japan</p>	<p>26P-7-35 Field Electron Emission Properties of Vertically Aligned Carbon Nanotube synthesized from Palm Oil Precursor A.B. Suriani 1,2, M.H. Mamat 1, M. Salina 1, N.A. Asli 1, M.S. Azmina 2, A.N. Falina 2, M. Maryam 1, M.S. Shamsudin 1, R. Md Nor 3 and M. Rusop 1, 1 Univ. Teknologi MARA, 2 Univ. Pendidikan Sultan Idris and 3 Univ. of Malaya, Malaysia</p>	<p>26P-7-36 Design and Fabrication of Three-dimensional Force Sensing Device with Carbon Nano-fiber Polymer Composites F.-Y. Chang 1, C.-M. Liu 2, T.-M. Chen 1 and C.-M. Chen 1, 1 Natl. Taiwan Univ. of Sci. and Technol. and 2 ITRI, Taiwan</p>
<p>26P-7-37 Carbon Nanotube for CO₂ Detection Sensors with Pt Adsorption Z.-D. Lin 1, C.-S. Huang 2, C.-H. Hsiao 3 and S.-J. Young 1, 1 Natl. Formosa Univ., 2 Natl. Yunlin Univ. and 3 Natl. Cheng Kung Univ., Taiwan</p>	<p>26P-7-38 In-situ Observation of Surface Graphitization of Gallium Droplet and Concentration of Carbon in Liquid Gallium R. Ueki 1,2, T. Nishijima 1,2, T. Hikata 3, S. Okubo 3, R. Utsunomiya 4, T. Matsuba 4, J. Fujita 1,2, 1 Tsukuba Res. Ctr. for Interdisciplinary Materials Sci., 2 Univ. of Tsukuba, 3 Sumitomo Electric and 4 Nissan Electric, Japan</p>	<p>26P-7-39 Preparation of Pt-decorated CNTs by DCC-activated Amidation and Investigation of their Electrochemical Properties Y.H. Kim and H.C. Choi, Chonnam Natl. Univ., Korea</p>
<p>Nanodevices</p>		
<p>26P-7-40 Multi-bit Characteristics of Cr/InSbTe (IST)/TiN Phase Change Memory Array Y.T. Kim 1, E.-B. Lee 1,2, Y.H. Kim 1 and C.K. Kim 1, 1 KIST and 2 Samsung Electronics, Korea</p>	<p>26P-7-41 Speed Enhancement of WSi₂ Nanocrystals Memory with Barrier Engineered Si₃N₄/HfAlO Tunnel Layer D.U. Lee 1, H.J. Lee 1, E.K. Kim 1, H.-w. You 2 and W.-J. Cho 2, 1 Hanyang Univ. and 2 Kwangwoon Univ., Korea</p>	<p>26P-7-42 Channel Recessed 1T-DRAM with ONO Gate Dielectric J.-K. Park and W.-J. Cho, Kwangwoon Univ., Korea</p>
<p>26P-7-43 Resistive Switching Effects in Ultrathin Metallic Junctions with Nanometer-scale Gap of Various Metals D. Ishida, K. Kobayashi, K. Matsushige and H. Yamada, Kyoto Univ., Japan</p>	<p>26P-7-44 Characteristics of Gate-all-around Poly-Si Nanowire TFT SONOS Nonvolatile Memory T.-Y. Liu, P.-C. Huang, C.C. Chen and J.-T. Sheu, Natl. Chiao Tung Univ., Taiwan</p>	<p>26P-7-45 Demonstration of ALD-TiN Gate FinFET with TDMAT Precursor for WFV Reduction T. Hayashida 1,2, K. Endo 3, Y.X. Liu 3, S. Ouchi 3, T. Matsukawa 3, W. Mizubayashi 3, S. Migita 3, Y. Morita 3, H. Ota 3, H. Hashiguchi 1, D. Kosemura 1, T. Kamei 1, J. Tsukada 3, Y. Ishikawa 3, H. Yamauchi 3, A. Ogura 1 and M. Masahara 1,3, 1 Meiji Univ., 2 JSPS and 3 AIST, Japan</p>
<p>26P-7-46 Carrier Transport Mechanisms of the Programming and Retention Characteristics for TANOS Flash Memory Devices D.H. Kim 1, J.H. You 1, D.U. Lee 1, T.W. Kim 1 and K.W. Lee 2, 1 Hanyang Univ. and Hynix Semiconductor, Korea</p>	<p>26P-7-47 Novel Protruded-shape Unipolar RRAM Structure for improving Switching Uniformity through Excellent Conductive Filament Controllability K.-C. Ryoo 1,2, J.-H. Oh 1,2, S. Jung 1, H. Jeong 2 and B.-G. Park 1, 1 Seoul Natl. Univ. and 2 Samsung Electronics, Korea</p>	<p>26P-7-48 Memristive Switching in a Single Oxide Nanowire T. Yanagida 1, K. Nagashima 1, K. Oka 1, M. Kanai 1, B.H. Park 2 and T. Kawai 1,2, 1 Osaka Univ., Japan and 2 Konkuk Univ., Korea</p>
<p>26P-7-49 Tri-gate Flash Memory with Improved IPD Layer T. Kamei 1, Y.X. Liu 2, T. Matsukawa 2, K. Endo 2, S. Ouchi 2, J. Tsukada 2, H. Yamauchi 2, Y. Ishikawa 2, T. Hayashida 1, K. Sakamoto 2, A. Ogura 1 and M. Masahara 1,2, 1 Meiji Univ. and 2 AIST, Japan</p>	<p>26P-7-50 Apply Low Energy Excimer Laser Annealing to improve Gold Nanocrystals Embedded Silicon Dioxide Thin Film K.-Y. Shen, Y.-Y. Wu and C.-H. Kuan, Natl. Taiwan Univ., Taiwan</p>	<p>26P-7-51 Direct Analysis of Backscattering Phenomenon from Drain Region of Silicon Nanodiode using NEGF Approach T. Tsutsumi and K. Tomizawa, Meiji Univ., Japan</p>
<p>26P-7-52 Single-string Carbon Nanotube Field Effect Transistors fabricated by Two-step Dielectrophoresis T.G. Kim 1, J.S. Hwang 1, Y.S. Yu 2, M.G. Kang 1 and S.W. Hwang 1, 1 Korea Univ. and 2 Hankyong Natl. Univ., Korea</p>	<p>26P-7-53 Extraction for Substrate-related Components of Vertical Junctionless Silicon Nanowire Field-effect Transistors and its Verification on RF Characteristics S. Shin 1, I.M. Kang 2 and K.R. Kim 1, 1 Ulsan Natl. Inst. of Sci. & Technol. and 2 Kyungpook Natl. Univ., Korea</p>	<p>26P-7-54 Effects of Contact Size and Schottky Barrier Height on Nanoscale Contact Resistance M.W. Ryu, Y. Kim, and K.R. Kim, Ulsan Natl. Inst. of Sci. & Technol., Korea</p>

<p>26P-7-55 Fabrication and Transport Properties in InAs-based Self Switching Nano-diodes T. Kiso 1, K. Nishisaka 1, T. Maemoto 1, S. Sasa 1, S. Kasai 2 and M. Inoue 1, 1 Osaka Inst. of Technol. and 2 Hokkaido Univ., Japan</p>	<p>26P-7-56 Extreme Shrinkage of Carbon Nanotubes induced by Supersonic Stress and Low-acceleration Electron Beam Irradiation T. Takahashi 1,2, R. Ueki 1,2, T. Hikata 3, S. Okubo 3, R. Utsunomiya 4, T. Matsuba 4 and J. Fujita 1,2, 1 Tsukuba Res. Ctr. for Interdisciplinary Materials Sci., 2 Univ. of Tsukuba, 3 Sumitomo Electric and 4 Nissin Electric, Japan</p>	<p>26P-7-57 Transport Electron Scattering due to Structural Defects in InSb Quantum Wells T.D. Mishima and M.B. Santos, Univ. of Oklahoma, USA</p>
<p>26P-7-58 Thermal Characteristics of a Single-electron-pump Refrigerator H. Ikeda 1, K. Miwa 1 and F. Sallelh 1,2, Shizuoka Univ. and 2 JSPS, Japan</p>	<p>26P-7-140L Impact of ZrO₂ on Electron Trapping Behavior in 28 nm HKMG nMOSFETs by RTN Analysis S.C. Tsai 1, S.L. Wu 2, B.C. Wang 1, S.J. Chang 1, J.F. Chen 1, P.C. Huang 1, D.G. Hong 2, C.H. Hsu 3, C.W. Yang 3, C.M. Lai 3, C.W. Hsu 3, O. Cheng 3, 1 National Cheng Kung Univ., 2 Cheng Shiu Univ. and United Microelectronics, Taiwan</p>	<p>26P-7-141L to 26P-4-5L L-Shaped Tunneling Field Effect Transistors (TFETs) for Low Subthreshold Swing and High Current Drivability S.W. Kim 1, W.Y. Choi 2, M. C. Sun 1, H.W. Kim 1, J. H. Lee 1, H. Shin 1 and B. C. Park 1, 1 Seoul Nat. Univ. and 2 Sogang Univ., Korea</p>
<p>26P-7-142L Channel Thickness Effect of Capacitorless Dynamic Random Access Memory on Silicon-On-Insulator Substrate S.-M. Jung and W.-J. Cho, Kwangwoon Univ., Korea</p>	<p>26P-7-143L Influence of Backgate Voltage on Spin Accumulation in a Silicon Nanowire Spin Valve J. Tarun,1,2, S. Huang 1, Y. Fukuma 1, H. Idzuchi 4, Y. Otani 1,4, T. Koderu 2, N. Fukata 3, K. Ishibashi 1,2 and S. Oda 2, 1 RIKEN, 2 Tokyo Inst. of Technol., 3 NIMS and 4 Univ. of Tokyo, Japan</p>	
Nanofabrication		
<p>26P-7-59 Si based High-index-contrast-grating Structure fabricated by High Temperature Cl₂ Inductively Coupled Plasma Etching using Thermal Nanoimprint Resist Mask A. Matsutani 1, Y. Hashidume 1, H. Ohtsuki 3 and F. Koyama 2, 1 Tokyo Inst. of Technol. and 2 Samco Internatl., Japan</p>	<p>26P-7-60 Trimming Lithography: An Effect of Multi-exposures Dose and Mask-shifted Position to the Sub-resolution Pattern Size and the Pattern Density A. Sriklat 1, N. Atthi 2, W. Jeamsaksiri 1, C. Hruanun 2, A. Poyai 2 and R. Silapunt 1, 1 King Mongkut's Univ. of Technol. and 2 Natl. Electronics & Computer Technol. Ctr., Thailand</p>	<p>26P-7-61 Rapid Fabrication of Sub-10-nm Silicon Pillars using a Natural Mask with RIE, Piranha Oxidation, and HF Wet Etching N. Atthi, K. Imai, J. Supadech, W. Jeamsaksiri, C. Hruanun and A. Poyai, Natl. Electronics & Computer Technol. Ctr., Thailand</p>
<p>26P-7-62 Excimer Laser Crystallization of a-Ge Quantum Dot Arrays on Si Substrate T.-W. Liao, Y.-K. Wu, C.-W. Chiu, H.-M. Chen and C.-H. Kuan, Natl. Taiwan Univ., Taiwan</p>	<p>26P-7-63 Synthesis of Semiconducting 3-D "Nano-tree" Hierarchical Nanostructures G.-J. Shin 1, J.-H. Lim 2, Y.-I. Lee 1, Y.-H. Choa 1 and N.V. Myung 3, 1 Hanyang Univ., 2 KIST, Korea and 3 Univ. of California-Riverside, USA</p>	<p>26P-7-64 Fabrication and Replication of Hemispherical Dome-shaped Hyperlens Array P.L. Chen 1, M.J. Huang 1, C.C. Chen 1, C.Y. Su 1, Y.H. Lin 1, N.N. Chu 1, M.H. Shiao 1 and H.N. Lin 2, 1 ITRI and 2 Natl. Tsing Hua Univ., Taiwan</p>
<p>26P-7-65 Fabrication of Nanocone Subwavelength Antireflection Structures on Quartz Substrate Y.-H. Tang, M.-J. Huang, J.-Y. Su, W.-H. Cho and M.-H. Shiao, Natl. Applied Res. Labs, Taiwan</p>	<p>26P-7-66 Molecular Dynamics Study on the Enhancement of Coverage of Trench-filling with Higher Aspect Ratio R.-T. Hong 1 and J.-Y. Yang 2, 1 China Univ. of Sci. & Technol. and 2 Natl. Taiwan Univ., Taiwan</p>	<p>26P-7-67 Electronic States Formation by Surface Atom Removal on a MoS₂ Surface N. Kodama 1, T. Hasegawa 1,2, T. Tsuruoka 1,2, C. Joachim 3 and M. Aono 1, 1 NIMS, 2 JST-CREST, Japan and 3 CEMES, France</p>
<p>26P-7-68 Pattern Transfer Characterization after Multi-level Lithography for a Fabrication of the 3-D AlTiC Air Bearing Surface of the Hard Disk Slider P. Pholprasit 1, 2, N. Atthi 2, T. Thammabut 3, W. Jeamsaksiri 1, C. Hruanun 2, A. Poyai 2 and R. Silapunt 1, 1 King Mongkut's Univ. of Technol., 2 Natl. Electronics & Computer Technol. Ctr. and 3 Western Digital, Thailand</p>	<p>26P-7-69 Thickness Dependence Characteristics of Aluminium-doped Zinc Oxide Nanorod Array-based Ultraviolet Photoconductive Sensor M.H. Mamat, N.I. Ishak, Z. Khusaimi, M.Z. Musa, M. Salina, N.D.Md. Sin, U.M. Noor and M. Rusop, Univ. Teknologi MARA, Malaysia</p>	<p>26P-7-70 Fabrication of GaNAs/AlGaAs Quantum Well Solar Cells M. Elborg 1,2, T. Noda 1, T. Mano 1, M. Jo 1 and K. Sakoda 1,2, 1 NIMS and 2 Univ. of Tsukuba, Japan</p>
<p>26P-7-71 High-aspect-ratio Carbon Nano-rod Tips carried out from scanning Electron Beam Deposition M.-N. Chang 1, Y.-H. Ku 1, P.-L. Chen 2, J. Su 2, M. Li 3 and A. Nemcsics 4, 1 Natl. Chung Hsing Univ., 2 Natl. Applied Res. Labs, 3 Natl. Chiao Tung Univ. and 4 Obuda Univ., Taiwan</p>	<p>26P-7-72 Fabrication Metal Thin Film Pattern in the Air M. Onoue and H. Ushijima, AIST, Japan</p>	<p>26P-7-73 Nano-hole Array Patterned Sapphire Fabrication by ICP-RIE C.M. Chang 1,2, D. Chiang 1, M.H. Shiao 1, C.T. Yang 3, M.J. Huang 1 and W.J. Hsueh 2, 1 Natl. Applied Res. Labs, 2 Natl. Taiwan Univ. and 3 ITRI, Taiwan</p>
<p>26P-7-74 Photolithography with Periodic Multilayered Resist Film for Photonic Crystals M. Shimoda, K. Nagato, T. Hamaguchi and M. Nakao, Univ. of Tokyo, Japan</p>	<p>26P-7-75 Surface, Structural, Optical, and Electrical Properties of Reactively Sputtered ZnO Thin Films with Oxygen Pressure I.-S. Park, Y.-W. Kim, H. Park, D.-K. Choi and J. Ahn, Hanyang Univ., Korea</p>	

Nanomaterials		
26P-7-76 Fabrication and Characterization BZCYYb Electrolyte Thin Films by E-beam Technique for IT-SOFC Y.S. Hong, H.W. Choi and H.H. Yoon, Kyungwon Univ., Korea	26P-7-77 Oxygen Vacancy Chain Formation Energy of Rutile TiO ₂ under Various Pressure Conditions and Electric Field: ab initio Calculations D.S. Yoo, K. Ahn, S.B. Cho and Y.-C. Chung, Hanyang Univ., Korea	26P-7-78 First Principles Study on Pr Doped Ceria and Pure Ceria of the Defective Structure considering Pressure Effect K. Ahn 1,2, D.S. Yoo 1, J.-h. Lee 2 and Y.-C. Chung 1, 1 Hanyang Univ. and 2 KIST, Korea
26P-7-79 Withdrawn Explanation of Thermoelectric Power and Resistivity of Zn Nanowires D. Prasad 1,2, K.K. Choudhary 1, N. Kaurav 3 and I. Mansuri 2,4, 1 Shri Vaishnav Inst. of Technol. & Sci., 2 Venkateshwar Inst. of Technol., 3 Holkar Sci. College and 4 Devi Ahilya Univ., India	26P-7-80 First-principles Simulation of Pyroelectricity in Single-domain Ferroelectric Bulks and Nanofilms K. Nakamura 1,2, 1 Kyoto Univ., Japan and 2 Egypt-Japan Univ. of Sci. & Technol., Egypt	26P-7-81 Synthesis of TiO ₂ Nanowires by Hydrothermal Method M.N. Asiah, M.F. Achoi, S. Abdullah and M. Rusop, Univ. Teknologi MARA, Malaysia
26P-7-82 Effect of Solvent on the Dielectric Properties of Nanocomposite PMMA:TiO ₂ Dielectric Films L.N. Ismail, N.N. Hafizah, M.S. Samsudin, S.H. Herman and M. Rusop, Univ. Teknologi MARA, Malaysia	26P-7-83 Electronic Transport Properties in Singly Crystalline TiO ₂ Nanorods H.Y. Tsai, C.A. Chen, W.C. Wang, R.S. Chen, Y.S. Huang, Natl. Taiwan Univ. of Sci. & Technol., Taiwan	26P-7-84 In situ High-resolution Transmission Electron Microscopy of Pt-Au-Pt Nanojunctions S. Kodama and T. Kizuka, Univ. of Tsukuba, Japan
26P-7-85 Formation of Silver Nanogaps using Electromigration H. Masuda and T. Kizuka, Univ. of Tsukuba, Japan	26P-7-86 Preparation of p-CuO/n-ZnO Nanowire Heterojunction Arrays filled with PMMA and their Optoelectronic Characteristics Y.-C. Tu 1, S.-J. Wang 1, F.-S. Tsai 1, Y.-W. Hsu 1, J.-C. Lin 1 and S.-I. Tsai 2, 1 Natl. Cheng Kung Univ. and 2 Natl. Univ. of Kaohsiung, Taiwan	26P-7-87 Withdrawn Synthesis and Application of Ag Nanowires in Touch Panel Displays J.-W. Kim, Y.-S. Kim, M.-G. Kwak and S.-J. Hong, Korea Electronics Technol. Inst., Korea
26P-7-88 Withdrawn Effect of Nano AlN in Epoxy on Heat Dissipation and Luminous Flux of High-brightness Light Emitting Diode Packages B.-J. Li 1, C.-H. Chang 1, Y.-K. Su 1, B. Chen 2 and K.-J. Gan 3, 1 Natl. Cheng Kung Univ., 2 Delta Electronics and 3 Natl. Chiayi Univ., Taiwan	26P-7-89 Influence of RF Magnetron Sputtering Condition on the ZnO Passivating Layer for Dye Sensitized Solar Cells S.W. Rhee, K.H. Kim and H.W. Choi, Kyungwon Univ., Korea	26P-7-90 Preparation of a Bimetallic Catalyst Layered Anode for Direct Biogas-fueled Solid Oxide Fuel Cells N.N.T. Quynh, Y.S. Hong and H.H. Yoon, Kyungwon Univ., Korea
26P-7-91 Optimization of Seeded Catalyst Layer for the Growth of Vertically Aligned Al-doped ZnO Nanorods Array for Optoelectronic Applications M.F. Malek, M.H. Mamat, M.Z. Sahdan, M.Z. Musa, Z.Khusaimi and M. Rusop, Univ. Teknologi MARA, Malaysia	26P-7-92 A New Synthetic Approach for the Preparation of Au-Ag Composite Nanorods through Proton Beam Irradiation Y.-J. Kim 1 and J.H. Song 2, 1 Chungnam Natl. Univ. and 2 Suncheon Natl. Univ., Korea	26P-7-93 Carrier Transport Mechanisms of Organic Bistable Devices utilizing Hybrid C ₆₀ /polymethylmethacrylate Nanocomposites C.H. Yoo, S.H. Ko and T.W. Kim, Hanyan Univ., Korea
26P-7-94 Withdrawn Nanostructuring of Polyurethanes by Highly Ordered Coordination Compounds of Transition Metals I.M. Davletbaeva, A.M. Gumerov and R.S. Davletbaev, Kazan State Technol. Univ., Russia	26P-7-95 Novel Nanohybrids of Silver Particles on Clay Platelets for inhibiting Silver-resistant Bacteria H.-L. Su 1, S.-H. Lin 1, J.-C. Wei 2 and J.-J. Lin 2, 1 Natl. Chung Hsing Univ. and 2 Natl. Taiwan Univ., Taiwan	26P-7-96 Withdrawn Preparation and Characterization of Low Dielectric Constant Polyimide Nanofoams E. Aram and S. Mehdipour Ataei, Iran Polymer & Petrochemical Inst., Iran
26P-7-97 Withdrawn Fabrication of Poly(9,9'-dioctylfluorene)-based Nano-micro Structures by Proton Beam Writing Y. Maeyoshi 1, K. Takano 1, A. Asano 1, H. Marui 1, M. Omichi 1, T. Satoh 2, T. Kamiya 2, Y. Ishii 2, T. Ohkubo 2, M. Koka 2, W. Kada 2, M. Sugimoto 2, H. Nishikawa 3, A. Saeki 1 and S. Seki 1, 1 Osaka Univ., 2 JAEA and 3 Shibaura Inst. of Technol., Japan	26P-7-98 Preparation and Characteristic of Room Temperature Ethanol Sensor based on Laterally Oriented ZnO Nanowires F.-S. Tsai, S.-J. Wang, Y.-C. Tu and J.-C. Lin, Natl. Cheng Kung Univ., Taiwan	26P-7-99 In Situ High-resolution Transmission Electron Microscopy of Tungsten Nanocontacts and Atomic-sized Wires H. Masuda and T. Kizuka, Univ. of Tsukuba, Japan
26P-7-144L Recent Development in Electron Energy Loss Spectroscopy and its Applications to Nanomaterial Analysis A. Maigné, Gatan, Japan	26P-7-145L Highly-Sensitive Differential-Mode Detection of Biomolecules Using Dual Extended-Gate MOSFETs J. Choi, H.-H. Lee, J.-I. Ahn, S.-H. Jo and J.-K. Shin, Kyungpook National Univ., Korea	
Nanoimprint, Nanoprint and Rising Lithography		
26P-7-100 Approach for Actual Line Width Measurement of 45 nm-hp UV-NIL Patterns by Extremely Shallow Si Etching K. Suzuki 1,2,3, S.-W. Youn 2,3, Q. Wang 2,3, H. Hiroshima 2,3 and Y. Nishioka 1, 1 Nihon Univ., 2 AIST and 3 JST-CREST, Japan	26P-7-101 Nanoimprint Roller Stamp Fabrication using Projective Step-and-flash Lithography and Electroless Nickel (EN) Deposition C.-L. Wu, Y.-C. Chu, Y.-C. Tsai and C.-K. Sung, Natl. Tsing Hua Univ., Taiwan	26P-7-102 Impact of Resist Shrinkage for 3D Patterns in Nanoimprint Lithography A. Horiba 1,2, N. Nishikura 1,2, R. Suzuki 1,2, M. Yasuda 1,2, H. Kawata 1,2 and Y. Hirai 1,2, 1 Osaka. Pref. Univ. and 2 JST-CREST, Japan

<p>26P-7-103 Whole-field Real-time Monitoring of Filling Process in UV Nanoimprint Lithography Q. Wang 1,2, H. Hiroshima 1,2, K. Suzuki 1,2 and S.-W. Youn 1,2, 1 AIST and 2 JST-CREST, Japan</p>	<p>26P-7-104 Throughput of UV Nanoimprint in Pentafluoropropane using Spin Coat Films under Thin Residual Layer Conditions H. Hiroshima 1,2 and K. Suzuki 2,3, 1 AIST, 2 JST-CREST and 3 Nihon Univ., Japan</p>	<p>26P-7-105 Simulation of the Resist Filling Time in 2-D and 3-D Patterns in UV Nanoimprint under Condensable Gas Ambient R. Suzuki 1,3, Y. Nagaoka 1, H. Hiroshima 2,3, H. Kawata 1,3 and Y. Hirai 1,3, 1 Osaka Pref. Univ., 2 AIST and 3 JST-CREST, Japan</p>
<p>26P-7-106 Thermal and Chemical Behaviors of 0.2-nm-high Stepped Glass Substrate Surface fabricated by Thermal Nanoimprint Process Y. Miyake 1, G. Tan 1, H. Oi 2, M. Mita 2, K. Sunagawa 3, S. Kaneko 1,4 and M. Yoshimoto 1, 1 Tokyo Inst. of Technol., 2 Kyodo Internatl., 3 Namiki Precision Jewel and 4 Kanagawa Industrial Technol., Japan</p>	<p>26P-7-107 Formation Mechanisms of Pattern Defects in Nanoimprint Lithography Y. Watanabe 1,2, H. Kawata 1,2, M. Yasuda 1,2 and Y. Hirai 1,2, 1 Osaka Pref. Univ. and 2 JST-CREST., Japan</p>	<p>26P-7-108 Fabrication of Relatively Large Microstructures on Polyimide using Hot Embossing R. Ikoma 1, H. Komatsuzaki 1, K. Suzuki 1, T. Komori 1, K. Kuroda 1, H. Saitou 1, S.-w. Youn 2, M. Takahashi 2, R. Maeda 2 and Y. Nishioka 1, 1 Nihon Univ. and 2 AIST, Japan</p>
<p>26P-7-109 Double Patterning by Room-temperature Nanoimprint using Organic Spin-on-glass M. Okada 1,2,3, Y. Haruyama 1,2 and S. Matsui 1,2, 1 Univ. of Hyogo, 2 JST-CREST and 3 JSPS, Japan</p>	<p>26P-7-110 Fabricated Various Metallic Nano Pattern using Ag Printing Technique S.-C. Oh, S.-H. Lee, K.-I. Kim and H. Lee, Korea Univ., Korea</p>	<p>26P-7-111 Properties of Microcontact Printing for Accurate and well-controlled MEMS Fabrication Processes T. Jean and N. Miki, Keio Univ, Japan</p>
<p>BioMEMS, Lab on a Chip</p>		
<p>26P-7-112 Detection of DNA Immobilization and Hybridization using Micro-grating Optical Biosensor N. Atthi 1, N. Chathirat 2, T. Osotchan 2, S. Dangtip 2, W. Jeamsaksiri 1, C. Hruanun 1 and A. Poyai 1, 1 Natl. Electronics & Computer Technol. Ctr. and 2 Mahidol Univ., Thailand</p>	<p>26P-7-113 A Simple Capacitive Sensor Array to measure Meso-scale Humidity Variation H.H. Lee 1, J. Choi 1, J. Ahn 1, C.-S. Kim 2 and J.-K. Shin 1, 1 Kyungpook Natl. Univ., Korea and 2 Missouri Univ. of Sci. & Technol., USA</p>	<p>26P-7-114 Photochemically Induced Crystallization of Proteins promoted on the Plasmonic Chip K. Tawa 1, S. Haruta 1,2, T. Okutsu 2 and J. Nishii 3, 1 AIST, 2 Gunma Univ. and 3 Hokkaido Univ., Japan</p>
<p>26P-7-115 Fluorescence Microscopic Observation of Neurons on a Plasmonic Chip C. Yasui 1,2, K. Tawa 1, C. Hosokawa 1, J. Nishii 3, H. Aota 2 and A. Matsumoto 2, 1 AIST, 2 Kansai Univ. and 3 Hokkaido Univ., Japan</p>	<p>26P-7-116 A Microfluidic Chip with Microweir Structure for Continuous Sample Separating and Collecting Applications S.K. Hsiung 1, H.C. Lee 2, S.R. Lin 1 and C.H. Lin 2, 1 Fooyin Univ. and 2 Natl. SunYat-Sen Univ., Taiwan</p>	<p>26P-7-117 Fabrication of Bioanode for Glucose/Oxygen Biofuel Cells by Glucose Oxidase Immobilization in a CNT Film S.Y. Lee, N. Lee and H.H. Yoon, Kyungwon Univ., Korea</p>
<p>26P-7-118 Electrokinetic Protein Preconcentration using Nanogaps generated by Electric Breakdown at the Junction Gaps C.-C. Kuo and C.-P. Jen, Natl. Chung Cheng Univ., Taiwan</p>	<p>26P-7-119 Sensitivity Enhancement of Immuno-pillar Chip using Magnetic Beads Stirrer T. Kasama 1,2, M. Tokeshi 1,2 and Y. Baba 1,2,3, 1 Nagoya Univ., 2 "The Knowledge Hub" of Aichi and 3 AIST, Japan</p>	<p>26P-7-146L Performance of NWFET-type Biosensor with a Microfluidic Channel S.-I. Kim, Y.H. Kim, C.K. Kim and Y.T. Kim, KIST, Korea</p>
<p>26P-7-147L A Novel Flow Sequencing Method on Centrifugal Microfluidic Device using "Liquid Clock" Y. Ukita 1, Y. Takamura 1 and Y. Utsumi 2, 1 JAIST and 2 Univ. of Hyogo, Japan</p>		
<p>Microsystem Technology and MEMS</p>		
<p>26P-7-120 A New Application of EN-based Cantilever for CMOS-MEMS Probe K.-Y. Lee, J.-T. Huang, H.-J. Hsu, G.-T. Jheng, C.-K. Chen and T.- C. Tsai, Natl. Taipei Univ. of Technol., Taiwan</p>	<p>26P-7-121 Using Electroless Nickel Plating Process to fabricate the CMOS-MEMS RF Probe with Amplitude Detector Circuits J.-T. Huang, G.-T. Jheng, K.-Y. Lee, C.-K. Chen and T.- C. Tsai, Natl. Taipei Univ. of Technol., Taiwan</p>	<p>26P-7-122 MEMS Contact of Test Socket for BGA IC Packages D. Lee 1,2, O.-h. Kwon 2, P.-H. Hong 2, J. Kim 3, J. Jeon 1,4, C. Cho 1, B. Kim 5 and J. Lee 1, 1 Kyungpook Natl. Univ., 2 M2Lab, 3 AITECH, 4 eFree System and 5 Catholic Univ. of Daegu, Korea</p>
<p>26P-7-123 Magnetic Micro Actuator using Interactive Force between Magnetic Elements K. Hatama, F. Tsumori, Y. Xu, H. Kang and H. Miura, Kyushu Univ., Japan</p>	<p>26P-7-124 Micromachined Inductor integrated with the Patterned Ferromagnetic Film Y.-C. Huang 1, B.-W. Jang 2, C.-L. Wu 2 and W. Fang 1, 1 Natl. Tsing Hua Univ. and 2 ITRI, Taiwan</p>	<p>26P-7-125 Square-patterned TiN Narrow-band Infrared Emitter J.T. Song 1, J.H. Park 1, J.C. Choi 1, H.T. Miyazaki 2 and S.H. Kong 1, 1 Kyungpook Natl. Univ. and 2 NIMS, Japan</p>
<p>26P-7-126 Fabrication of Electrostatically-driven Fused Quartz Double-ended Tuning Fork (DETF) Resonator using Quartz-on-quartz Bundling Technique E.-S. Song 1, S.-M. Kang 2, K.-J. Park 2, H. Kim 2, Y.-K. Kim 1, J.-E. Ahn 3 and C.-W. Baek 2, 1 Seoul Natl. Univ., 2 Chung-Ang Univ. and 3 Agency for Defense Develop., Korea</p>	<p>26P-7-127 High Sensitivity Fiber-optic Fabry-perot Interferometer Temperature Sensor X. Li, S. Lin, J. Liang, H. Oigawa and T. Ueda, Waseda Univ., Japan</p>	<p>26P-7-128 Electrowetting Lens employing Hemispherical Cavity formed by HNA Etching J.K. Lee 1, H.-R. Kim 1, E. Jeong 2, W.I. Jang 2 and S.H. Kong 1, 1 Kyungpook Natl. Univ. and 2 Electronics & Telecommunications Res. Inst., Korea</p>
<p>26P-7-129 The Distributed Bragg Reflectors Waveguide infiltrated by Liquid-crystal D.-P. Cai, H.-Y. Pan and C.-C. Chen, Natl. Ctrl. Univ., Taiwan</p>	<p>26P-7-130 Development of a New Exposure Tool for Laser-scan Delineation of Precise Helical Patterns onto Sub-50-micron Wires T. Horiuchi and R. Sasaki, Tokyo Denki Univ., Japan</p>	<p>26P-7-131 Atmospheric Non-thermal Pressure Plasma-jet System for PDMS Bonding Process K. Kim 1, G. Kim 1, Y. Oh 2, T.-G. Park 3, D.C. Han 3 and S.S. Yang 1, 1 Aju Univ., 2 AMED and 3 Seoul Natl. Univ., Korea</p>

<p>26P-7-132 Inkjet Printed Polymer Micro Rivet S.-A. Kuo, G.-H. Lu and C.-Y. Lo, Natl. Tsing Hua Univ., Taiwan</p>	<p>26P-7-133 Metalized Movable Microstructures produced by the Combination of Two-photon Microfabrication and Electroless Plating T. Ikegami 1, M.P. Stocker 2, K. Monaco 2, J.T. Fourkas 2 and S. Maruo 1, 1 Yokohama Natl. Univ., Japan and 2 Univ. of Maryland, USA</p>	<p>26P-7-134 High-resolution Wet Etching Technology of Electroless Nickel Alloy Film on High Topography Surface for MEMS Application Y. Zhang 1, A. Toda 2, T. Kobayashi 1, T. Itoh 1 and R. Maeda 1, 1 AIST and 2 Meltex, Japan</p>
<p>26P-7-135 Fabrication of pn Junction at the Wall of Deep Trench for Near-infrared Sensor A. Baba, N. Uryu and S. Sumi, Kyushu Inst. of Technol., Japan</p>	<p>26P-7-136 Direct Photo-etching of Fluorocarbon Polymers induced by High Energy Synchrotron Radiation H. Kido 1, M. Ishizawa 1, T. Azeta 1, Y. Ukita 2 and Y. Utsumi 2, 1 Univ. of Hyogo and 2 JAIST, Japan</p>	<p>26P-7-137 Catalytic Etching for fabricating Micro-scale Silicon Structure M.J. Huang 1, N.N. Chu 1, C.R. Yang 2, Y.H. Tang 1, C.M. Chang 1 and M.H. Shiao 1, 1 Natl. Applied Res. Labs and 2 Natl. Taiwan Normal Univ., Taiwan</p>
<p>26P-7-148 Fabrication of BeCu Probe Array using Heating and Fusing Current D. Lee 1, S. Kim 1, D. Kong 1, C. Cho 1, B. Kim 2, J. Lee 1 and O.-H. Kwon 1, 1 Kyungpook Natl. Univ. and 2 Catholic Univ. of Daegu, Korea</p>	<p>26P-7-149 Vertical Direction MEMS Probe Card B. Kim 1, B. Lee 2, H.C. Kim 3 and K. Chun 4, 1 Catholic Univ. of Daegu, 2 Korea Univ. of Technol. & Edu. 3 Univ. of Ulsan and 4 Seoul Natl. Univ., Korea</p>	

Room A and P (2F)

Banquet

18:30-20:30

Prof. Namba Award Ceremony

Performance by Maiko/Geiko and Samurai Workshop

Thursday, October 27

Room A (2F)	Room B (2F)	Room C (2F)
27A-8: Nanoimprint, Nanoprint and Rising Lithography I Chairpersons: H. Hiroshima (AIST) I. Bergmair (PROFAXTOR)	27B-8: Nanomaterials III Chairpersons: T. Chikyo (NIMS)	27C-8: Nanofabrication I Chairpersons: S. Shingubara (Kansai Univ.) K. Kita (Univ. of Tokyo)
27A-8-1 9:00 Multilayer Nanoimprint Lithography Technology and its Applications (<i>Invited</i>) J. LEE, Korea Inst. of Machinery & Materials, Korea	27B-8-1 9:00 Optical Studies of Dislocation-free GaAs Nano-wires grown on Trenched Si (001) Substrate by Cathode-luminescence L. Lee 1, K.-F. Chien 1, W.-C. Chou 1, C.-H. Ko 2, C.-H. Wu 2, Y.-R. Lin 2, C.-T. Wan 2, C.H. Wann 2, C.-W. Hsu 3, Y.-F. Chen 3 and Y.-K. Su 3, 1 Natl. Chiao Tung Univ., 2 Taiwan Semiconductor Manufacturing and 3 Natl. Cheng Kung Univ., Taiwan	27C-8-1 9:00 Fabrication and Characterization of Floating-gate Type MOS Capacitors with Nanoscale Triangular Cross-section Tunnel Areas Y.X. Liu 1, R.F. Guo 1, T. Kamei 2, T. Matsukawa 1, K. Endo 1, S. O'uchi 1, J. Tsukada 1, H. Yamauchi 1, Y. Ishikawa 1, T. Hayashida 2, K. Sakamoto 1, A. Ogura 2 and M. Masahara 1, 1 AIST and 2 Meiji Univ., Japan
27A-8-2 9:30 Three-dimensional Imprint Molds fabricated using Femtosecond Laser Nonlinear Lithography H. Nishiyama 1, Y. Hirata 2 and J. Nishii 1, 1 Hokkaido Univ. and 2 Osaka Univ., Japan	27B-8-2 9:20 Fabrication of New Planar Magneto-electronic Devices based on Regularly Arranged MnAs Nanoclusters M.T. Elm 1, P.J. Klar 2 and S. Hara 1,3, 1 Hokkaido Univ., Japan, 2 Justus-Liebig Univ., Germany and 3 JST -PRESTO, Japan	27C-8-2 9:20 Electrical Characterization of Flash Memory Structure with Vanadium Silicide Nano-particles D. Kim 1, D.U. Lee 1, H.J. Lee 1, S.G. Cho 1, E.K. Kim 1 and W.-J. Cho 2, 1 Hanyang Univ. and 2 Kwangwoon Univ., Korea
27A-8-3 9:50 Optical and Electrical Characterization of Insertion Structures for Transparent Metal Electrode prepared by Nanoimprint Lithography and CMP Process C.-M. Chen, C.-F. Ho, C.-W. Hsieh and C.-K. Sung, Natl. Tsing Hua Univ., Taiwan	27B-8-3 9:40 Fabrication and Optical Property of GaAs Nanowire Array for Solar Cell Applications E. Nakai 1, M. Yoshimura 1, K. Tomioka 1,2 and T. Fukui 1, 1 Hokkaido Univ. and 2 JST-PREST, Japan	27C-8-3 9:40 Stability of Metal Filaments in Solid Electrolyte Based Resistive Switching Devices I. Sapezanskaia 1, A. Nayak 2, I. Valov 1,3, T. Hasegawa 2, R. Waser 1,3 and M. Aono 2, 1 RWTH-Aachen Univ., Germany, 2 AIST, Japan and 3 Inst. for Solid State Res., Germany
27A-8-4 10:10 Impact of Polymer Resins on High Aspect Nano Pattern Replication by Thermal Nano-imprint Lithography H. Noma 1, J. Sakamoto 1,2, N. Nishikura 1,2, H. Kawata 1,2, M. Yasuda 1,2 and Y. Hirai 1,2, 1 Osaka Pref. Univ. and 2 JST-CREST, Japan	27B-8-4 10:00 Microscopic Study of the Germanium Nanowires grown at Low-temperatures by Au-catalysed Chemical Vapour Deposition M. Simanullang, K. Usami, T. Koderu, K. Uchida and S. Oda, Tokyo Inst. of Technol., Japan 27B-8-5 10:20 Memristor using a Single Oxide Nanowire -Performance in Ultra Small Memory and Intrinsic Mechanism- K. Nagashima 1, T. Yanagida 1,2, K. Oka 1, M. Kanai 1, J.-S. Kim 3, B.H. Park 3 and T. Kawai 1,3, 1 Osaka Univ., 2 JST-PRESTO, Japan and 3 Konkuk Univ., Korea	27C-8-4 10:00 Additional Electrochemical Treatment Effects on the Switching Characteristics of Anodic Aluminum Oxide ReRAM S. Otsuka 1, R. Takeda 1, S. Furuya 1, H. Miyake 2, T. Shimizu 2, S. Shingubara 2, N. Iwata 1, T. Watanabe 1, Y. Takano 1 and K. Takase 1, 1 Nihon Univ. and 2 Kansai Univ., Japan
Room P (2F)		
Coffee Break		
Room A (2F)	Room B (2F)	Room C (2F)
27A-9: Nanoimprint, Nanoprint and Rising Lithography II Chairpersons: A. Yokoo (NTT) J.J. Lee (Korea Inst. of Machinery & Materials)	27B-9: Nanomaterials IV Chairpersons: T. Tanii (Waseda Univ.) T. Chikyo (NIMS)	27C-9: Nanofabrication I Chairpersons: T. Hasegawa (NIMS) M. Masahara (AIST)
27A-9-1 10:45 Single and Multilayer Negative Index Materials fabricated by Nanoimprint Lithography (<i>Invited</i>) I. Bergmair 1, B. Dastmalchi 2, M. Bergmair 2, G. Hesser 2, M. Losurdo 3, G. Bruno 3, C. Helgert 4, E. Pshenay-Severin 4, T. Pertsch 4, E.-B. Kley 4, U. Hübner 5, R. Penciu 6, N.-H. Shen 6, M. Kafesaki 6, C.M. Soukoulis 6, K. Hingerl 2 and M. Muehlberger 1, 1 Profactor GmbH, 2 Johannes Kepler Univ. Linz, Austria, 3 Friedrich-Schiller-Universität Jena, 4 Inst. of Photonic Technol., Germany and 5 Foundation for Res. & Technol., Greece	27B-9-1 10:55 In Situ Observation of Atomistic Electromigration Processes in Platinum Nanocontacts S. Kodama and T. Kizuka, Univ. of Tsukuba, Japan	27C-9-1 10:35 Si/Ge Photonics for Communication and Sensing Applications (<i>Invited</i>) Y. Ishikawa, Univ. of Tokyo, Japan

27A-9-2 11:15 Large-area Nanotemplate Process and its Application to Roll Imprint J.-H. Choi, S.-W. Lee, J.-H. Lee, D.-G. Choi, J.-H. Jeong and E.-S. Lee, Korea Inst. of Machinery & Materials, Korea	27B-9-2 11:15 Tuning of the Plasmon Band of Metal Nanoparticle Thin Films Y. Tanoue and K. Sugawa, Nihon Univ., Japan	27C-9-2 11:05 Size Control of Tapered Cones for High Density Quantum Dots as 1.55 μm Emitters J.-H. Huh 1, C. Hermannstädter 1, K. Akahane 2, N.A. Jahan 1, H. Sasakura 1, M. Sasaki 2 and I. Suemune 1, 1 Hokkaido Univ. and 2 Natl. Inst. of Inform. & Communication Technol., Japan
27A-9-3 11:35 A Study on Fabrication Process of Capacity-equalized Mold by Electron Beam Lithography and Grayscale Laser Beam Lithography S.-W. Youn 1,2, S.-C. Park 1, K. Suzuki 1,2, Q. Wang 1,2 and H. Hiroshima 1,2, 1 AIST and 2 JST-CREST, Japan	27B-9-3 11:35 Electrochemical Characterization of Modified Gold Electrode based on Nano Porous Silicon for Amperometric Urea Biosensor D.H. Yun, S.W. Hwang and S.I. Hong, Korea Univ., Korea	27C-9-3 11:25 The 3-D Nanostructure Fabrication by controlling Downward Growth on Focused-ion-beam Chemical Vapor Deposition D.J. Guo, R. Kometani, S. Warisawa and S. Ishihara, Univ. of Tokyo, Japan
27A-9-4 11:55 Step and Repeat UV Nanoimprinting under Pentafluoropropane Gas Ambient S. Iyoshi 1,5, M. Okada 1,5,6, K. Kobayashi 3,5, S. Kaneko 3,5, T. Katase 2, K. Tone 2, Y. Haruyama 1,5, M. Nakagawa 3,5, H. Hiroshima 4,5 and S. Matsui 1,5, 1 Univ. of Hyogo, 2 MEISHO KIKO, 3 Tohoku Univ., 4 AIST, 5 JST-CREST and 6 JSPS, Japan	27B-9-4 11:55 Ultrafast and Efficient Photoresponse up to Room Temperature by Coherent Coupling between Excitons and Radiation Wave M. Ichimiya 1,2, H. Yasuda 3, M. Ashida 2, K. Mochizuki 2, H. Ishihara 3 and T. Itoh 2, 1 Osaka Dent. Univ., 2 Osaka Univ. and 3 Osaka Pref. Univ., Japan	27C-9-4 11:45 Strained Carbon Nanomechanical Resonator Fabrication from SU-8 by FIB/EB Dual-beam Lithography and Annealing Treatment R. Kometani, K. Kuroda, S. Warisawa and S. Ishihara, Univ. of Tokyo, Japan
27A-8, 9 Author's Interview: 12:15-12:25		27C-9-5 12:05 Mask-free Patterning and Modifications on Polysilicon Nanobelt Devices H.H. Liu, Y.S. Lin and J.T. Sheu, Natl. Chiao Tung Univ., Taiwan
	27B-8, 9 Author's Interview: 12:15-12:25	27C-8, 9 Author's Interview: 12:25-12:35
LUNCH		
Room A (2F)	Room B (2F)	Room C (2F)
27A-10: Resists Materials and Processing Chairpersons: K. Nozaki (Fujitsu) K. Okamoto (Hokkaido Univ.)	27B-10: Nano-Tool Chairpersons: S. Akita (Osaka Pref. Univ.) T. Ono (Tohoku Univ.)	27C-10: Nanofabrication I Chairpersons: K. Takase (Nihon Univ.) A. Kohno (Fukuoka Univ.)
27A-10-1 13:50 Directly Patternable Metal Oxides as High Selectivity Resists for Nanofabrication (Invited) A. Grenville, Inpria, USA	27B-10-1 13:50 Optically-driven Nano Robotic for Advanced Micro Biomedicine (Invited) K. Ikuta, Univ. of Tokyo, Japan	27C-10-1 14:00 Integration of Photo-assisted Atomic Switches T. Hino 1, T. Hasegawa 1, H. Tanaka 2, T. Tsuruoka 1, Y. Okawa 1, J.P. Hill 1, Y. Wakayama 1, K. Ariga 1, T. Ogawa 2 and M. Aono 1, 1 NIMS and 2 Osaka Univ., Japan
27A-10-2 14:20 In Situ Dissolution Analysis of Ultrathin EUV Resists J.J. Santillan and T. Itani, EIDEC, Japan	27B-10-2 14:20 Cantilevered Multilayer Graphene Mechanical Oscillator Y. Yuasa 1, A. Yoshinaka 1, T. Arie 1,2 and S. Akita 1,2, 1 Osaka Pref. Univ. and 2 JST-CREST, Japan	27C-10-2 14:20 Oxide Thickness Dependence of a Large Magnetoresistance Switching Phenomenon in a Ferromagnetic Nano-conduction Path K. Shimomura, T. Kato, T. Iwakura, T. Shimizu and S. Shingubara, Kansai Univ., Japan
27A-10-3 14:40 Limit of Line Edge Roughness at High Exposure Dose in Chemically Amplified Resists T. Kozawa, Osaka Univ., Japan	27B-10-3 14:40 Vacuum-packaged Resonant Thermal Sensor for Biological Cell in Liquid N. Inomata, M. Toda and T. Ono, Tohoku Univ., Japan	27C-10-3 14:40 Transformation from InAs Quantum Dots to Disks for Reduced Excitation-state Splitting S. Sakurai, S. Odashima, H. Iijima and I. Suemune, Hokkaido Univ., Japan
27A-10-4 15:00 Characterization of Fogging and Develop Loading Effects in Electron-beam Direct-writing Technology J. Kon 1, Y. Kojima 2, Y. Takahashi 2, T. Maruyama 2 and S. Sugatani 2, 1 Fujitsu Labs and 2 e-Shuttle, Japan	27B-10-4 15:00 Contactless Determination of Local Sheet Resistivity using Magnetic Force Microscopy F. Wakaya, M. Kajiwara, S. Abo and M. Takai, Osaka Univ., Japan	27C-10-4 15:00 Epitaxial-template Structures utilizing GOI Stripe-arrays and Hexagonal-meshes with Nano-spacing for Advanced Heterogeneous Integration on Silicon Platform A.M. Hashim 1,2, M. Anisuzzaman 1, S. Muta 1, T. Sadoh 1 and M. Miyao 1, 1 Kyushu Univ., Japan and 2 Univ. Teknologi Malaysia, Malaysia
27A-10 Author's Interview: 15:20-15:30	27B-10 Author's Interview: 15:20-15:30	27C-10 Author's Interview: 15:20-15:30

Room P (2F)		
Coffee Break		
27P-11: 15:30-17:30 POSTER SESSION II		
Resist Materials and Processing		
27P-11-1 Theoretical Study of Ionization of Polymers for EUV Resist M. Endo 1,2 and S. Tagawa 1,2, 1 Osaka Univ. and 2 JST-CREST, Japan	27P-11-2 Improvements in Pattern Collapse Margin and LWR in Thin-films for both E-beam and ArF Resists for sub-22nm Patterning I. Servin 1, B. Icard 1, H. Kandaschow 2, J. Cameron 3, M. Hellion 4, C. Sourd 1, J. Pradelles 1 and L. Pain 1, 1 CEA-Leti, France, 2 Dainippon Screen, Germany, 3 Dow Electronic Materials, USA and 4 Dow Electronic Materials, France	27P-11-3 Alternative Developers for ZEP-520 as a High-resolution Positive and Negative Tone Electron Beam Resist M.A. Mohammad 1, K. Koshelev 1,2, T. Fito 1,2, M. Stepanova 1,2 and S.K. Dew 1, 1 Univ. of Alberta and 2 Natl. Inst. for Nanotechnol. Canada
27P-11-4 Acid Generation Efficiency in Resist Films after Exposure to the 61 nm Free-electron Laser Light K. Okikawa 1, K. Okamoto 1,2, T. Kozawa 2,3, T. Hatsui 2, M. Nagasono 2, T. Kameshima 2, T. Togashi 2,4, K. Tono 2, M. Yabashi 2, H. Kimura 2,4, Y. Senba 4, H. Ohashi 2, R. Fujiyoshi 1 and T. Sumiyoshi 1, 1 Hokkaido Univ., 2 RIKEN, 3 Osaka Univ. and 4 JASRI, Japan	27P-11-5 Fabrication of Submicron Structures by Thermal Lithography J.K. Chen 1, J.W. Lin 1, J.P. Chen 2 and K.C. Chiu 2, 1 Natl. Taipei Univ. of Technol. and 2 ITRI, Taiwan	27P-11-6 Sensitivity of Process Parameters on Pattern Formation of Litho-cure-litho-etch Process S.-K. Kim, Hanyang Univ., Korea
27P-11-140L Study on Dissolution Behavior of Polymer bound PAG and blended PAG Resists by using Quartz Crystal Microbalance Method H. Yamamoto 1,2, T. Kozawa 1,2, S. Tagawa 1,2, 1 Osaka Univ. and 2 JST-CREST, Japan	27P-11-141L Solvated Electron Reaction with Some Polymer Bound Acid Generators or New Acid Generators R. Joshi 1,2, H. Yamamoto 1,2, K. Enomoto 1,2 and S. Tagawa 1,2, 1 Osaka Univ. and 2 JST-CREST, Japan	27P-11-142L Study on Resist Performance of Polymer Bounded Photo-acid Generators (PAG) and blended PAG D.N. Tuan 1,2, H. Yamamoto 1,2 and S. Tagawa 1,2, 1 Osaka Univ. and 2 JST-CREST, Japan
Nanocarbons		
27P-11-7 to 26P-7-17 Atomic Layer Deposition of Amorphous Carbon and Multilayer Graphene using Carbon Tetrabromide as Carbon Solid Source T. Choi, H. Kang, J. Yoon, H. Jung and H. Kim, Yonsei Univ., Korea	27P-11-8 Microscopic Raman Mapping of Epitaxial Graphene on 4H-SiC(0001) R. O 1, A. Iwamoto 1, Y. Nishi 1, Y. Funase 1, T. Yuasa 1, T. Tomita 1, M. Nagase 1, H. Hibino 2 and H. Yamaguchi 2, 1 Univ. of Tokushima and 2 NTT, Japan	27P-11-9 A Structural Investigation of Carbon Nanofilaments in the Marimo Carbon Formation by the Methane Decomposition with Oxidized Diamond-supported Nickel Catalysts K. Komatsu 1, K. Nakagawa 2, H. Gamo 3, M. Eguchi 4, T. Ando 5 and M. N-Gamo 1, 1 Toyo Univ., 2 Kansai Univ., 3 Toppan Printing, 4 Ibaraki Univ. and 5 NIMS, Japan
27P-11-10 Fabrication of Flexible Thin Film Transistors using Singlewalled Carbon Nanotubes and Graphene S.J. Kim, S. Aikawa, B. Hou, E. Einarsson, S. Chiashi and S. Maruyama, Univ. of Tokyo, Japan	27P-11-11 Synthesis and Device Application of Nitrogen-doped Single-walled Carbon Nanotubes by Plasma CVD M. Akutsu, T. Kato, S. Kuroda, T. Kaneko and R. Hatakeyama, Tohoku Univ., Japan	27P-11-12 Formation of Fin-like Ridge-structures of Graphene on Graphene/SiC(0001) by Molecular Beam Epitaxy F. Maeda and H. Hibino, NTT, Japan
27P-11-13 Tailoring Magnetism of Fe on Graphen with Uniaxial Strains: an Ab initio Study H. Choi and Y.-C. Chung, Hanyang Univ., Korea	27P-11-14 Band-gap Engineering of Hydrogen-potassium Ternary Graphite Intercalation Compound Thin Films Y. Takagi 1,2 and S. Okada 1,2, 1 Univ. of Tsukuba and 2 JST-CREST, Japan	27P-11-15 Growth and in-situ Observations of Ferromagnetic Metal Encapsulated Multi-walled Carbon Nanotubes synthesized by Microwave Plasmaenhanced Chemical Vapor Deposition Y. Hayashi 1, T. Tokunaga 2, Y. Horita 2, T. Iijima 1, T. Yanagimoto 3, K. Kaneko 3, U. Suryavanshi 1, M. Tanemura 1 and K. Kuroda 2, 1 Nagoya Inst. of Technol., 2 Nagoya Univ. and 3 Kyushu Univ., Japan
27P-11-16 Temperature Dependent Resistance of Multi-wall Carbon Nanotube E. Kawabe, S. Itaya, K. Hirahara and Y. Nakayama, Osaka Univ., Japan	27P-11-17 Graphene Growth from Spin-coated Polystyrene without a Flammable Gas S. Suzuki 1, Y. Takei 1,2, K. Furukawa 1 and H. Hibino 1, 1 NTT and 2 Tokyo Univ. of Sci., Japan	27P-11-18 Controlling the Graphene Layer in Thermal Chemical Vapor Deposition by Substrate Bias H.-C. Chang, C.-C. Li, Y.-T. Shih, J.-R. Huang, W.-J. Su and K.-Y. Lee, Natl. Taiwan Univ. of Sci. & Technol., Taiwan
27P-11-19 Hole Doping leads to Magnetism in Nanographene S. Dutta and K. Wakabayashi, NIMS, Japan	27P-11-20 Withdrawn Carbon Nanotubes and Carbon Nanocoils grown by Chemical Vapor Deposition on Graphene Sheets Supported Pd Nanoparticles K.J. Chung 1, C.A. Wang 1, N.W. Pu 1, Y. Sung 2, Y.M. Liu 1 and M.D. Ger 1, 1 Natl. Defense Univ. and 2 Chung Shan Inst. of Sci. & Technol., Taiwan	27P-11-21 Synthesis of Iron-encapsulated Carbon Nanocapsules and Carbon Nanotubes using Iron-doped Fullerene Nanowhiskers D. Matsuura 1, K. Miyazawa 2 and T. Kizuka 1, 1 Univ. of Tsukuba and 2 NIMS, Japan

<p>27P-11-22 Withdrawn Growth of Graphene Thin films by Polymer Carbon Source based Chemical Vapor Deposition G.N. Shi 1, N.W. Pu 1, Y.M. Liu 1, N.T. Wen 2, Y. Sung 2 and M.D. Ger 1, 1 Natl. Defense Univ. and 2 Chung Shan Inst. of Sci. & Technol., Taiwan</p>	<p>27P-11-23 Withdrawn Enhancing Electron Field Emission Properties of Ultra nanocrystalline Diamond by growing on Textured Si Substrate P.-C. Huang 1, W. C. Shih 1, K. Y. Teng 2 and I.N. Lin 2, 1 Tatung Univ. and 2 Tamkang Univ., Taiwan</p>	<p>27P-11-24 An Investigation on Current Saturation Mechanism of Carbon Nanotube FETs B.P. Algul and K. Uchida, Tokyo Inst. of Technol., Japan</p>
<p>27P-11-25 Fabrication and Characterization of Carbon Nanotube Sheet drawn from Vertically Aligned Carbon Nanotube Forest T. Iijima 1, H. Oshima 2, T. Ito 1, Y. Inagaki 1, Y. Hayashi 1, U.B. Suryavanshi 1 and M. Tanemura 1, 1 Nagoya Inst. of Technol. and 2 Denso, Japan</p>	<p>27P-11-26 Effect of H₂O₂ Aqueous Solution on Preferential Inactivation of Metallic Single Walled Carbon Nanotubes using UV Irradiation H. Tabata, K. Imakoga and M. Katayama, Osaka Univ., Japan</p>	<p>27P-11-27 Growth of Graphene from SU-8-2002 Photoresist Material on Nickel Substrate H. Lee, J. Hong, S.G. Lee, J.-H. Lee, T. Choi, H. Kang, J. Yoon, H. Jung, H. Kim and T. Lee, Yonsei Univ., Korea</p>
<p>27P-11-28 Thermal Durability of FIB-DLC Films containing W A. Fujimoto 1, M. Okada 1, Y. Kang 1, M. Niibe 1, S. Matsui 1, T. Suzuki 2 and K. Kanda 1, 1 Univ. of Hyogo and 2 Nagaoka Univ. of Technol., Japan</p>	<p>27P-11-29 Multiple Exciton Generation by a Single Photon in Single-walled Carbon Nanotubes S. Konabe 1,2 and S. Okada 1,2, 1 Univ. of Tsukuba and 2 JST-CREST, Japan</p>	<p>27P-11-30 Broadband Patch Absorber using Multi-walled Carbon Nanotubes J.-K. Chuang, C.-J. Hsiao, R.-Y. Fang, C.-L. Wang and K.-Y. Lee, Natl. Taiwan Univ. of Sci. & Technol., Taiwan</p>
<p>27P-11-31 Growth and Characterization of Carbon Nanotube on ZnO Films by Microwave Plasma Jet Chemical Vapor Deposition C.H. Su and C.M. Huang, Natl. Taipei Univ. of Technol., Taiwan</p>	<p>27P-11-143L Direct Synthesis of Graphene on SiO₂ Substrates Using Transfer-Free Processes K. Gumi, Y. Ohno, K. Maehashi, K. Inoue, and K. Matsumoto, Osaka Univ., Japan</p>	<p>27P-11-144L Impacts of the Access Resistance on the Channel Conduction Characteristics in Graphene FETs M.-H. Jung 1, C. Quan 1, H. Fukidome 1, T. Suemitsu 1,2, T. Otsuji 1,2 and M. Suemitsu 1,2, 1 Tohoku Univ. and 2 JST-CREST, Japan</p>
<p>27P-11-145L Low Temperature Synthesis of Single-Walled Carbon Nanotubes in a High Vacuum using Pt Catalyst in Alcohol Gas Source Method N. Fukuoka 1, Y. Mizutani 1, T. Maruyama 1, S. Naritsuka 1 and S. Iijima 1,2, 1 Meijo Univ. and 2 AIST, Japan</p>	<p>27P-11-146L Local Strain Distribution of Free-standing Graphene on Polymethylmethacrylate T. Kadowaki 1,2, T. Nishijima 1,2, R. Ueki 1,2, and J. Fujita 1,2, 1 Tsukuba Res. Center for Interdisciplinary Materials Sci. and 2 Univ. of Tsukuba, Japan</p>	
<p>Nanodevices</p>		
<p>27P-11-32 Heterojunction Photodiodes based on Honeycomb Structures for Ultraviolet Detection S.-Y. Tsai 1, J.-H. Lee 2 and M.-H. Hon 1, 1 Natl. ChengKung Univ. and 2 ITRI, Taiwan</p>	<p>27P-11-33 Withdrawn Photoresponse Behaviour and Mechanism of Multi-walled carbon Nanotubes copper Sulphide (Mwnt-cus) Hybrid Nanostructures Z. Zhan, C. Liu, L. Zheng, G. Sun, B. Li and Q. Zhang, Nanyang Technological Univ., Singapore</p>	<p>27P-11-34 Withdrawn Nanoporous Silicon Alcohol Vapor Sensor N. Atiwongsangthong, King Mongkut's Inst. of Technol., Thailand</p>
<p>27P-11-35 Enhanced Photo-conductivity of Silicon Nanowires conjugated with 3-aminopropyltriethoxysilane (APTES)-adsorbed Zn(OEP) Molecules M.S. Choi 1, D.J. Lee 1, Y.S. Kim 1, H.J. Kim 3, J.H. Lee 1,2, D.H. Yun 1, H.J. Shim 1, S.I. Hong 1, D. Whang 1,2 and S.W. Hwang 1, 1 Korea Univ., 2 Sungkyunkwan Univ. and 3 Kumoh Natl. Inst. of Technol., Korea</p>	<p>27P-11-36 Effects of Aluminum Doping and Electrode Distance on the Performance of Aligned Zinc Oxide Nanorod Array-based Ultraviolet Photoconductive Sensor M.H. Mamat, Z. Khusaimi, M.Z. Musa and M. Rusop, Univ. Teknologi MARA, Malaysia</p>	<p>27P-11-37 Designing and Characterization of Plasmonic Terahertz (THZ) Detectors based on Silicon MOSFET using Technology-cad H.C. Hwang 1, K. Park 1, W.-K. Park 2, S.-T. Han 2 and K.R. Kim 1, 1 Ulsan Natl. Inst. of Sci. & Technol. and 2 Korea Electrotechnol. Res. Inst., Korea</p>
<p>27P-11-38 Withdrawn On nanowire Band graded Si:Ge Photodetectors G. J. Kim, H. S. Lee, Y. J. Cho, J. E. Yang, R.R. Lee, J.K. Lee and M. H. Jo, POSTECH, Korea</p>	<p>27P-11-39 Withdrawn Synthesis of Coral like Nanobranched TiO₂ Structure and its Application to Dye sensitized Solar Cells P. H. Wang 1, S. J. Wang 1, P. Chen 1, K. M. Uang 2, T. M. Chen 3 and T. C. Wang 1, 1 Natl. Cheng Kung Univ. and 2 WuFeng Univ., Taiwan</p>	<p>27P-11-40 Control Theory of Near-field Optical Energy Transfer in One-dimensional Waveguide consisting of Metallic Nanoparticles by vibrating External Field S. Tanaka 1, H. Hattori 1, S. Hidaka 1 and T. Iida 1,2, 1 Osaka Pref. Univ. and 2 JST-PRESTO, Japan</p>
<p>27P-11-41 Fabrication of Organic Electroluminescence Devices by Means of Electropray Deposition H. Anzai, Y. Watanabe and T. Sakamoto, Kogakuin Univ., Japan</p>	<p>27P-11-42 Formation of Nanometer-scale Patterns on the n-GaN Surface and its Application to GaN-based Vertical Light-emitting Diodes K.S. Shin 1, H.-M. An 1, J.I. Sim 1, S.J. Kim 1, S. Oh 2, M. Yoo 2 and T.G. Kim 1, 1 Korea Univ. and 2 Verticle, Korea</p>	<p>27P-11-43 Light Extraction Enhancement of GaN-based Light Emitting Diodes using Laser Lithography Technique J.-T. Chen, W.-C. Lai, Y.-J. Kao, Y.-Y. Yang and J.-K. Sheu, Natl. Cheng Kung Univ., Taiwan</p>
<p>27P-11-44 n-ZnO / InAs QDs / p-GaAs Pillar Structure prepared as a Single Quantum Dot Emitter H. Iijima, S. Odashima and I. Suemune, Hokkaido Univ., Japan</p>	<p>27P-11-45 Photocurrent Measurements on a Quantum Cascade Laser Device by Fourier Transform Infrared Microscope E.C. Enobio, K. Ohtani, Y. Ohno and H. Ohno, Tohoku Univ., Japan</p>	<p>27P-11-46 Electrical Control of the Exciton Fine Structure splitting in GaAs Island Quantum Dots for the Generation of Polarization-entangled Photons M. Ghali, K. Ohtani, Y. Ohno and H. Ohno, Tohoku Univ., Japan</p>

<p>27P-11-47 Self-assembled Growth of Ferromagnetic Semiconductor-ferroelectric Insulator Nanocomposite Structures using a Pulsed Laser Deposition Method T. Sakamoto, A.N. Hattori, T. Kanki and H. Tanaka, Osaka Univ., Japan</p>	<p>27P-11-48 Collision Based Computing using Single-electron Circuits S. Hayashi and T. Oya, Yokohama Natl. Univ., Japan</p>	<p>27P-11-49 Analysis on Dynamic Behavior of Thermally Driven Single-electron Stochastic Resonance S. Kasai, Y. Shiratori and K. Miura, Hokkaido Univ., Japan</p>
<p>27P-11-50 Performance Characteristics of Electric Double Layer Capacitor containing Graphene as an Electrode Combining Vertically Aligned Carbon Nanotube and RuO₂ Nanostructures Y.-T. Shih, C.-C. Li, H.-C. Chang, K.-Y. Lee, P.-H. Chen, S.-J. Liou, Y.-M. Chen and Y.-S. Huang, Natl. Taiwan Univ. of Sci. & Technol., Taiwan</p>		
Nanofabrication		
<p>27P-11-51 Fabrication of High Transconductance InZnO Transparent Thin Film Transistors by Sol-gel Method Y. Fujihara, T. Maemoto, S. Sasa and M. Inoue, Osaka Inst. of Technol., Japan</p>	<p>27P-11-52 Thin Semiconductor Films Deposition based on Electron Injection into Solutions from Nanosilicon Ballistic Emitter T. Ohta, H. Yoshimura, B. Gelloz and N. Koshida, Tokyo Univ. of Agri. & Technol., Japan</p>	<p>27P-11-53 Local Deposition of Colloidal Gold Nanoparticles from an AFM Tip using Dielectrophoresis K. Miyamoto, K. Kaisei, K. Kobayashi, H. Yamada and K. Matsushige, Kyoto Univ., Japan</p>
<p>27P-11-54 Fabrication of an Ordered Anodic Aluminum Oxide Pore Arrays with an Interpore Distance smaller than the Nano-indentation Pitch formed by Ion Beam Etching C. Wang 1, Y. Ishida 1, Q. Wang 1, T. Yamaguchi 1, S. Tanaka 2, K. Saitoh 1, T. Shimizu 1 and S. Shingubara 1, 1 Kansai Univ. and 2 Natl. Inst. of Info. & Communications Technol., Japan</p>	<p>27P-11-55 Fabrication of 6-nm-sized Nanodots using Self-assemble of Polystyrene-poly (Dimethyl Siloxane) M. Huda, J. Liu, Y. Yin and S. Hosaka, Gunma Univ., Japan</p>	<p>27P-11-56 Fabrication of Dense n-type Phthalocyanine Nano-rod Array H. Saeki, M. Nishimoto, Y. Koshiba, M. Misaki, S. Horie, K. Ishida and Y. Ueda, Kobe Univ., Japan</p>
<p>27P-11-57 Stiffened Ribs Design for Micro Products fabricated by Two-photon Polymerization T.-T. Chung, C.-L. Tseng, C.-P. Hung and C. Huang, Natl. Taiwan Univ., Taiwan</p>	<p>27P-11-58 Withdrawn Thermal Stability of Cu₂WN/Si Nano-via Contact Structures Y.-H. Hwang 1,2, W. J. Cho 1, Y.H. Kim 2 and Y.T. Kim 2, 1 Kwangwoon Univ. and 2 KIST, Korea</p>	<p>27P-11-59 Nano Order Size ZnO Particles fabricated by Electro Spray Pyrolysis Y. Ishikawa 1,2, T. Doe 1,2, M. Horita 1,2, T. Nishida 1,2 and Y. Uraoka 1,2, 1 Nara Inst. of Sci. & Technol. and 2 JST-CREST, Japan</p>
<p>27P-11-60 Patterning and Carbonization of Block Copolymer Self-assembled Structures by Focused-ion-beam S. Warisawa, R. Mitsuhashi, R. Kometani and S. Ishihara, Univ. of Tokyo, Japan</p>	<p>27P-11-61 Influence of Rapid High Temperature postannealing in Thermal Formation of Self-organized Nanogroove Array on the Epitaxial Oxide Thin Film Surface R. Yamauchi 1, K. Kobayashi 2, T. Suzuki 2, G. Tan 1, D. Shiojiri 1, S. Kaneko 1,3 and M. Yoshimoto 1, 1 Tokyo Inst. of Technol., 2 Taiyo Yuden and 3 Kanagawa Industrial Technol. Ctr., Japan</p>	<p>27P-11-62 Observation of Collective Molecular Motion on a Gold Surface M. Han and M. Kaneta, Tokyo Inst. of Technol., Japan</p>
<p>27P-11-63 Withdrawn Microstructure and Optical Characteristics of Ga-doped ZnO Nanowalls by Hydrothermal Method C.-S. Huang 1, J.-Y. Wu 1, S.-J. Young 2, C.-W. Liu 3 and C.-H. Hsiao 3, 1 Natl. Yunlin Univ., 2 Formosa Univ. and 3 Natl. Cheng Kung Univ., Taiwan</p>	<p>27P-11-64 Large-scale SiGe/Si Superlattice Quantum Dot Arrays fabricated by Nanosphere Lithography S.W. Lee, B.L. Wu and S.L. Cheng, Natl. Cent. Univ., Taiwan</p>	<p>27P-11-65 High Resolution and High Density Nano-patterning in HSQ using Proximity Correction D.K. Brown 1, E. Kim 1, C. Chapin 1, G. Lopez 2, N. Unal 2 and U. Hofmann 2, 1 Georgia Inst. of Technol., USA and 2 GenISys, Germany</p>
<p>27P-11-66 The Modeling and Correction of Lateral Resist Development Effects in 3D Electron-beam Lithography V.A. Guzenko 1, N. Belic 2, N. Unal 2, A. Schleunitz 1 and C. David 1, 1 Paul Scherrer Inst., Switzerland and 2 GenISys, Germany</p>	<p>27P-11-67 Use of Self-assembled Peptide Nanostructures for the Fabrication of Silicon Nanowires K. Andersen, J. Castillo-León, T. Bakmand and W.E. Svendsen, Technical Univ. of Denmark, Denmark</p>	<p>27P-11-147L Impact of Oxide Thinning on Resistance Switching Behavior of RF Sputtered SiO_x Dielectric Sandwiching with Pt Electrodes A. Ohta 1, Y. Goto 1, S. Nishigaki 1, H. Murakami 1, S. Higashi 1 and S. Miyazaki 2, 1 Hiroshima Univ. and 2 Nagoya Univ., Japan</p>
Nanomaterials		
<p>27P-11-68 Preparation of Fower-shaped Silver Nanomaterials via Pulsed Proton Beam Irradiation Y.-J. Kim 1 and J.H. Song 2, 1 Chungnam Natl. Univ. and 2 Sunchon Natl. Univ., Korea</p>	<p>27P-11-69 Withdrawn Surface, Structural, and Optical Property Variation of ZnO Nanoparticles formed on Si Substrates due to Thermal Treatment B.C. Park, Y.S. No, S.Y. Kim and T.W. Kim, Hanyang Univ., Korea</p>	<p>27P-11-70 Silica-encapsulated ZnSe Nanocrystals prepared by AOT Microemulsions A. Lee, J.H. Kim, H.H. Yoon and S.J. Park, Kyungwon Univ., Korea</p>

<p>27P-11-71 Room Temperature Ferromagnetism in Nanocrystalline ZnO (core)/Crystalline Carbon (shell) synthesized by Thermal Decomposition Method M. Subramanian , M. Tanemura , T. Hihara and Y. Hayashi , Nagoya Inst. , of Technol., Japan</p>	<p>27P-11-72 Preparation and Characterization of Magnetic Chitosan Nanoparticles and its Encapsulation Efficiency for Fluorouracil H.-C. Yang 1 and M.-H. Hon 2, 1 Kun Shan Univ. and 2 Natl. Cheng Kung Univ., Taiwan</p>	<p>27P-11-73 Quantitative Analysis of Enrofloxacin using Dye Doped Silica Nanoparticle J.-A. Ko, S.-J. Kim, J.-W. Ahn and H.-B. Lim, Dankook Univ., Korea</p>
<p>27P-11-74 Morphological Observations of Size-controlled Squid Ink Particles on Electrodes and Insulated Substrates T. Matsuura 1, T. Kato 1, S. Todo 1, M. Horii 1, K. Minato 2 and T. Ueno 2, 1 Hokkaido Univ. of Edu. and 2 Hakodate Natl. College of Technol., Japan</p>	<p>27P-11-75 Photocatalyst ZnO Nanocrystalline Thin Films formed on Si Substrates R. Kasahara 1, S. Harako 1, S. Komuro 2 and X. Zhao 1, 1 Tokyo Univ. of Sci. and 2 Toyo Univ., Japan</p>	<p>27P-11-76 Stability of a Nano-sized Formulation by using Gamma-irradiation Technique under Stress Test for Development of Agro-formulation H.-J. Park, J.-S. Choi, H.-J. Kim and D.H. Kim, Korea Atomic Energy Res. Inst., Korea</p>
<p>27P-11-77 The Study of Topotactic Transformation from Te Nanowires into Ag₂Te with Single Crystalline D. Jeong 1, Y.-I. Lee 1, J.-H. Lim 2, N.V. Myung 3 and Y.-H. Choa 1, 1 Hanyang Univ., 2 Korea Inst. of Materials Sci., Korea and 3 Univ. of California-Riverside, USA</p>	<p>27P-11-78 Transition of Nanoparticle Structures by Evaporation of Solvent Mixture M.S. Kim , S. Lee and T. Lee , Yonsei Univ., Korea</p>	<p>27P-11-79 Characterization of ZnO Tetrapods prepared by a Simple Oxidation of Zn Plate in Air Atmosphere D.-h. Bae and G.-H. Lee, Dong-eui Univ., Korea</p>
<p>27P-11-80 Growth and Characterization of Nano-structured Zinc Tungstate (ZnWO₄) prepared by Microwave-assisted Synthesis M.K. Tsai 1, Y.C. Lee 1, C.C. Huang 1, S.Y. Hu 2, J.W. Lee 3, B.Y. Hong 4, B.J. Chen 1 and K.K. Tiong 4, 1 Tungkang Univ., 2 Tung Fang Design Univ., 3 Ming Chi Univ. of Technol. and 4 Natl. Taiwan Ocean Univ., Taiwan</p>	<p>27P-11-81 Hydrothermal Synthesis of Silicon-based Hollow Nanostructures S. Sonae, M. Ara and H. Tada, Osaka Univ., Japan</p>	<p>27P-11-82 Effect of Potassium Chloride Concentration on the Structural and Optical Properties of ZnO Nanorods grown on Indium-tin-oxide Film Coated Glass Substrates H.Y. Yang, Y.S. No and T.W. Kim, Hanyang Univ., Korea</p>
<p>27P-11-83 Preparation of Naturally-textured Al-doped ZnO Films on Flexible Substrate with Radio Frequency Magnetron Sputtering M.K. Prosad, Y.B. Kim, J.H. Lee and B.H. Choi, Korea Inst. of Industrial Technol., Korea</p>	<p>27P-11-84 Influence of Annealing Temperature on the Properties of TiO₂/ZnO Nanocomposite Film prepared by Simultaneous RF-magnetron Sputtering M.H. Abdullah, M.Z. Musa, L.N. Ismail, M.H. Mamat and M. Rusop, Univ. Teknologi MARA, Malaysia</p>	<p>27P-11-85 Effect of Inhomogeneous Strain Distribution on the Thickness Modulation in GaAs/GaAsP Strained Superlattice X.G. Jin 1, H. Nakahara 1, K. Saitoh 1, T. Saka 2, T. Ujihara 1, N. Tanaka 1 and Y. Takeda 1, Nagoya Univ. and 2 Daido Univ., Japan</p>
<p>27P-11-86 Photoluminescence and X-ray Absorption Fine Structure Analysis of Sm-doped TiO₂ Thin Films J. Sakurai 1, R. Kasahara 1, T. Ohtsuki 1, S. Harako 1, S. Komuro 2, N. Hirao 3 and X. Zhao 1, 1 Tokyo Univ. of Sci., 2 Toyo Univ. and 3 JAEA, Japan</p>	<p>27P-11-87 Structural Characteristics of Zinc Oxide Films treated in Ar/O₂ Atmosphere using Microwave Plasma Jet Sintering System C.H. Su and C.M. Huang, Natl. Taipei Univ. of Technol., Taiwan</p>	<p>27P-11-88 Optical Properties of ZnO/MgO Multilayer Films with Different Pairs grown by Sputtering Technique Y.C. Lee 1, F.J. Cheng 1, M.K. Tsai 1, S.Y. Hu 2, J.W. Lee 3, Z.K. Wun 4 and K.K. Tiong 4, 1 Tungkang Univ., 2 Tung Fang Design Univ., 3 Ming Chi Univ. of Technol. and 4 Natl. Taiwan Ocean Univ., Taiwan</p>
<p>27P-11-89 Effect of Oxygen Gas Flow Rate on the Properties ZnO:Ga Films deposited by Facing Target Sputtering System K.-H. Lee, H.-W. Choi and K.H. Kim, Kyungwon Univ., Korea</p>	<p>27P-11-90 Fabrication of Al₂O₃/SiC Nanocomposite using SiC Nanopowder synthesized by Mechanical Alloying Method S. Kangwantrakool, Suranaree Univ. of Technol., Thailand</p>	
<p>Nano Tool</p>		
<p>27P-11-91 Nano-scale Force Studies of PSL Spheres on a Si Substrate using Atomic Force Microscopy S.P. Pan, W.E. Fu, H.C. Liou, T.C. Yu and C.L. Wu, ITRI, Taiwan</p>	<p>27P-11-92 Picosecond Snapshot of Surface Morphology by using Coherent Soft X-ray Pulses T. Tomita 1, N. Hasegawa 2, K. Terakawa 3, M. Yamamoto 1, Y. Minami 3, Y. Ochi 2, T. Kaihori 2, M. Nishikino 2, M. Yamagiwa 2, T. Kawachi 2 and T. Suemoto 3, 1 Univ. of Tokushima, 2 JAEA and 3 Univ. of Tokyo, Japan</p>	<p>27P-11-93 Highly Sensitive Detection of Target Biomolecules on a Cell Surface using Metal Nano-particles conjugated with Aptamer Probes H. Kim 1, H. Terazono 1, M. Hayashi 1, H. Takei 1,2 and K. Yasuda 1,3, 1 Kanagawa Academy of Sci. & Technol., 2 Toyo Univ. and 3 Tokyo Medical and Dental Univ., Japan</p>
<p>27P-11-94 Three Dimensional Nano-micro Processing for Polymer Films by MeV Ion Beam Lithography K. Takano 1, A. Asano 1, Y. Maeyoshi 1, H. Marui 1, M. Omichi 1, A. Saeki 1, S. Seki 1, T. Satoh 2, T. Kamiya 2, Y. Ishii 2, T. Ohkubo 2, M. Koka 2, W. Kada 2, M. Sugimoto 2 and H. Nishikawa 3, 1 Osaka Univ., 2 JAEA and 3 Shibaura Inst. of Technol., Japan</p>	<p>27P-11-95 Microchanneled Resonant Heat Sensor for a Living Cell M. Toda, T. Otake, N. Inomata and T. Ono, Tohoku Univ., Japan</p>	<p>27P-11-96 The Application of Advanced TEM Tomography for 3-dimensional Microstructure Analysis in Nanomaterials and Nanodevices S.-C. Lo and M.-W. Lai, ITRI, Taiwan</p>

<p>27P-11-97 Theoretical Study for Mechanical Control of Micro- and Nano-mechanical Systems by Cavity-induced Radiation Force N.D. Vy 1, R. Ooka 1 and T. Iida 1,2, 1 Osaka Pref. Univ. and 2 JST-PRESTO, Japan</p>	<p>27P-11-98 Coupled Mechanical Si Resonators and its Entrainment Condition K. Tanno and T. Ono, Tohoku Univ., Japan</p>	<p>27P-11-99 Oscillation of Cantilevered Multiwall Carbon Nanotubes by Thermal Actuation A. Yoshinaka 1, T. Arie 1,2 and S. Akita 1,2, 1 Osaka Pref. Univ. and 2 JST-CREST, Japan</p>
<p>27P-11-100 The Application of Tomography and Electrical Measurement in DB-FIB System for Cathode Materials of Li-battery S.-C. Lo, M.-W. Lai and L.-J. Lin, ITRI, Taiwan</p>	<p>27P-11-101 Planar-waveguide Based Optical Transducer M.-W. Lai, C.-S. Chu, S.-C. Lo, Y.-T. Li and Y.-C. Pu, ITRI, Taiwan</p>	<p>27P-11-148L Recognition of embedded Defects in suspended Nanowires using a Carbon-nanotube Cantilever Gat Y.-W. Lan 1,2, L.-N. Nguyen 2,3, S.-J. Lai 2, M.-C. Lin 2, C.-H. Kuan 1 and C.-D. Chen 2,4, 1 Natl. Taiwan Univ. 2 Academia Sinica, 3 Natl. Tsing Hua Univ. and 4 Natl. Chen-Kung Univ., Taiwan</p>
<p>27P-11-149L-Withdrawn Controlling Phase Formation of Co@Fe₂O₃ Heteroparticles and CoFe₂O₄ Nanoparticles B. Nakhjavan, M.N. Tahir, U. Kolb and W. Tremel, Johannes Gutenberg Universität, Germany</p>		
<p>Nanoimprint, Nanoprint and Rising Lithography</p>		
<p>27P-11-102 Silica/UV-cured Resin Nanocomposites for Replica Molds in UV Nanoimprinting S. Kudo 1, C.M. Yun 1,2, K. Nagase 1, S. Kubo 1,2 and M. Nakagawa 1,2, 1 Tohoku Univ. and 2 JST-CREST, Japan</p>	<p>27P-11-103 Changes in Weight and Viscosity of UV-curable Resins and Monomers by absorbing a Condensable Pentafluoropropane Gas Effective in UV Nanoimprint S. Kaneko 1, K. Kobayashi 1, Y. Tsukidate 1,2, H. Hiroshima 2,3, S. Matsui 2,4 and M. Nakagawa 1,2, 1 Tohoku Univ., 2 JST-CREST, 3 AIST and 4 Univ. of Hyogo, Japan</p>	<p>27P-11-104 Evaluation of Polymerization Degrees of Patterns fabricated by UV-nanoimprint in PFP Gas Ambient Y. Sawada 1,6, M. Okada 1,6,7, H. Miyake 2, T. Ohsaki 3, Y. Haruyama 1,6, Y. Hirai 4,6, H. Hiroshima 5,6 and S. Matsui 1,6, 1 Univ. of Hyogo, 2 Daicel Chemical Industries, 3 Toyo Gosei, 4 Osaka Pref. Univ., 5 AIST, 6 JST-CREST and 7 JSPS, Japan</p>
<p>27P-11-105 Evaluation of Fluorinated Self-assembled Monolayers under Pentafluoropropane Gas Ambient by Scanning Probe Microscopy M. Okada 1,4,5, M. Iwasa 2, Y. Haruyama 1,4, H. Hiroshima 3,4 and S. Matsui 1,4, 1 Univ. of Hyogo, 2 SII Nanotechnol., 3 AIST, 4 JST-CREST and 5 JSPS, Japan</p>	<p>27P-11-106 Evaluation of Interaction Force between UV-nanoimprint Resin and Antisticking Layer by Dynamic Contact Angle Measurement M. Chinen 1,2, M. Okada 1,2,3, Y. Haruyama 1,2 and S. Matsui 1,2, 1 Univ. of Hyogo, 2 JST-CREST and 3 JSPS, Japan</p>	<p>27P-11-107 Micro Thermal Imprinting on Powder-polymer Multilayer Substrate Y. Xu, F. Tsumori, K. Hatama, H. Kang and H. Miura, Kyushu Univ., Japan</p>
<p>27P-11-108 The Development of Electroformed Ni-W Mold to Thermal Imprinting for Borosilicate Glass M. Yasui 1, S. Kaneko 1, M. Takahashi 2, Y. Hirabayashi 1, T. Ozawa 1 and R. Maeda 2, 1 Kanagawa Industrial Technol. Ctr. and 2 AIST, Japan</p>	<p>27P-11-109 Change in Young's Modulus of Imprinted Nanopillar after Residual Layer Removal by Reactive Ion Etching Y. Kang 1,2,3, Y. Nakai 1,2, M. Okada 1,2,3, Y. Haruyama 1,2 and S. Matsui 1,2, 1 Univ. of Hyogo, 2 JST-CREST and 3 JSPS, Japan</p>	<p>27P-11-110 Comparison of Surface Characterization of Antisticking Layer formed by CVD and Dip-coat Methods for Nanoimprint Lithography D. Yamashita 1,2, M. Okada 1,2,3, Y. Nakai 1,2, Y. Haruyama 1,2 and S. Matsui 1,2, 1 Univ. of Hyogo, 2 JST-CREST and 3 JSPS, Japan</p>
<p>27P-11-111 Fabrications of Various Al Doped ZnO Nano-patterns delived by Sol-gel Method and Direct Nano-imprint Lithography J.S. Kim, K.-J. Byeon, J.-Y. Cho, S.-C. Oh and H. Lee, Korea Univ., Korea</p>	<p>27P-11-112 Transfer Printing Method to obtain Polarized Light Emission in OLED H.Y. Noh 1, C.-S. Park 1, J.-S. Park 1, M.-K. Park 1, J.-W. Kim 2, T.-H. Yoon 2, S.-W. Kang 1 and H.-R. Kim 1, 1 Kyungpook Natl. Univ. and 2 Pusan Natl. Univ., Korea</p>	<p>27P-11-113 Biomimetic Nanostructured Broadband Antireflection Coating and its Application on Crystalline Solar Cells J.Y. Chen and K.W. Sun, Natl. Chiao Tung Univ., Taiwan</p>
<p>27P-11-114 Imprinted Pattern Profile-dependent Plasmonic and Optical Properties J.-H. Choi, S.-J. Park, C.-H. Kim, J.-H. Lee, D.-G. Choi, E.-S. Lee and J.-H. Jeong, Korea Inst. of Machinery & Materials, Korea</p>		
<p>BioMEMS, Lab on a Chip</p>		
<p>27P-11-115 Investigation of Hot Roller Embossing to fabricate Serpentine Microfluidic Mixer C.-W. Tsao and T.-Y. Chen, Natl. Cent. Univ., Taiwan</p>	<p>27P-11-116 HF-etched Glass Substrate for the Optical Readout of Sol-gel Microarrays J.-Y. Ahn 1, H.A. Kim 1, S.W. Lee 1, Y.H. Cho 2 and S. Kim 1, 1 Dongguk Univ. and 2 Seoul Natl. Univ. of Technol., Korea</p>	<p>27P-11-117 Fabrication of Miniaturized High Frequency Quartz Crystal Microbalance using Wet Etching Process J. Liang 1, X. Li 2, H. Li 1 and T. Ueda 2, 1 Southeast Univ. and 2 Waseda Univ., Japan</p>
<p>27P-11-118 Measurement of Nonlinear Mechanical Properties of Surfactant-added PDMS (Polydimethylsiloxane) H.T. Kim, S.B. Lee, C.K. Oh, D.K. Lee and O.C. Jeong, INJE Univ., Korea</p>	<p>27P-11-119 Minimization of Artifacts in Electrical Stimulation with Extracellular Potential Measurement T. Kaneko, F. Nomura and K. Yasuda, Tokyo Medical & Dental Univ., Japan</p>	<p>27P-11-120 Imaging Optical System expanded Depth of Field for Direct Observation of Cells in Microfluidics A. Hattori 1, M. Hayashi 2 and K. Yasuda 1,2, 1 Tokyo Medical & Dental Univ. and 2 Kanagawa Academy of Sci. & Technol., Japan</p>

<p>27P-11-121 Comparison of Micromanipulation Systems using Electrophoresis and Dielectrophoresis by the Upper Limit of Traveling Rate of Microparticles or Cells in Various Solutions M. Hayashi 1, H. Kim 1, H. Terazono 1, A. Hattori 2 and K. Yasuda 1,2, 1 Kanagawa Academy of Sci. & Technol. 2 Tokyo Medical & Dental Univ., Japan</p>	<p>27P-11-122 Development of a Constitutive Cell-chip Measurement with Human Cardiomyocytes by using on-chip Cell Multi Electrode Assay T. Hamada, F. Nomura, T. Kaneko and K. Yasuda, Tokyo Medical & Dental Univ., Japan</p>	
Microsystem Technology and MEMS		
<p>27P-11-123 Fabrication of High Frequency Probe Chip by CMOS-MEMS and EN/IG Processes K.-Y. Lee, J.-T. Huang, G.-T. Jheng, H.-J. Hsu, C.-K. Chen and T.-C. Tsai, Natl. Taipei Univ. of Technol., Taiwan</p>	<p>27P-11-124 Micro-optical Pickup based on Ultra Precision Machining Optical Film J.-H. Hsu 1, C.-H. Lee 2 and R. Chen 1, 1 Natl. Tsing Hua Univ. and 2 Feng Chia Univ., Taiwan</p>	<p>27P-11-125 to 26P-7-148 Fabrication of BeCu Probe Array using Heating and Fusing Current D. Lee 1, S. Kim 1, D. Kong 1, C. Cho 1, B. Kim 2, J. Lee 1 and O. H. Kwon 1, 1 Kyungpook Natl. Univ. and 2 Catholic Univ. of Daegu, Korea</p>
<p>27P-11-126 to 26P-7-149 Vertical Direction MEMS Probe Card B. Kim 1, B. Lee 2, H.C. Kim 3 and K. Chun 4, 1 Catholic Univ. of Daegu, 2 Korea Univ. of Technol. & Edu. 3 Univ. of Ulsan and 4 Seoul Natl. Univ., Korea</p>	<p>27P-11-127 The Interference Effect of Rayleigh Wave and Intersecting Shear-horizontal Wave H. Oh, K. Lee, H. Lee, K. Lee and S.S. Yang, Ajou Univ., Korea</p>	<p>27P-11-128 Development of the Thermal-actuators fabricated by FIB-CVD Y. Nakai 1, Y. Kang 1, M. Okada 1,2, Y. Haruyama 1 and S. Matsui 1, 1 Univ. of Hyogo and 2 JSPS, Japan</p>
<p>27P-11-129 Luminescent Solar Concentrator for Flat Panel Display C.-H. Yeh 1, F.-Y. Chang 2, T.-Y. Hsieh 3 and H.-T. Young 1, 1 Natl. Taiwan Univ., 2 Natl. Taiwan Univ. of Sci. & Technol. and 3 Wintek, Taiwan</p>	<p>27P-11-130 Fabrication of Nickel Micro-lens Dies using Precise Hemispherical Resist Molds H. Ono and T. Horiuchi, Tokyo Denki Univ., Japan</p>	<p>27P-11-131 Implementation of a CMOS MEMS Lorentz Force Actuator for Optical Scanning Stage C.M. Sun 1, C.L. Wu 2, C. Wang 1 and W. Fang 1, 1 Natl. Tsing Hua Univ. and 2 ITRI, Taiwan</p>
<p>27P-11-132 LIGA-like Vertical Contact Probe H.-J. Hsu 1,2, S.-J. Wang 1, K.-Y. Lee 1,2, Y.-C. Wang 1, C.-C. Lan 1, M.-C. Chung 1 and J.-T. Huang 1,2, 1 C.C.P.Contact Probes and 2 Natl. Taipei Univ. of Technol., Taiwan</p>	<p>27P-11-133 Low-cost MEMS Fabrication based on Trench Integrated Cavity Wafer G. Zhao, T. Kobayashi, J. Lu, H. Takagi, Y. Zhang, T. Itoh and R. Maeda, AIST, Japan</p>	<p>27P-11-134 Nanoporous Gold as Low Temperature Bonding Intermediate W.-S. Wang 1, Y.-C. Lin 1, L.Y. Chen 1, M.W. Chen 1, T. Gessner 1,2,3 and M. Esashi 1, 1 Tohoku Univ., Japan, 2 Fraunhofer ENAS and 3 Chemnitz Univ. of Technol., Germany</p>
<p>27P-11-135 Effects of Specimen Dimensions on Adhesive Shear Strength between Micro-sized SU-8 Columns and Si Substrate C. Ishiyama, T. Tasaki, T.-F.M. Chang and M. Sone, Tokyo Inst. of Technol., Japan</p>	<p>27P-11-136 — Withdrawn Observation of Magnetization Process in GaMnAs using a Mechanical Cantilever K. Onomitsu, I. Mahboob, H. Okamoto and H. Yamaguchi, NTT, Japan</p>	<p>27P-11-137 Design of a GaAs-based Air-slot Photonic Crystal Nanocavity for Optomechanical Oscillators M. Nomura and K. Hirakawa, Univ. of Tokyo, Japan</p>
<p>27P-11-138 Optimal Size Determination of Electrodes for High Frequency Fundamental AT-cut Quartz Resonator using 3-D FEM J. Ji, H. Ohigawa, H. Chen, M. Zhao and T. Ueda, Waseda Univ., Japan</p>	<p>27P-11-139 Vibration Analysis of Original Shape Quartz Resonator for High Q Realization H. Oigawa, Y. Kirino, H. Chen, J. Ji and T. Ueda, Waseda Univ., Japan</p>	<p>27P-11-150L Crystal Grain Positioning of Organic Semiconductor Film Using Electrostatic Inkjet Y. Ishida 1 and T. Asano 2, 1 Yasukawa Electric and 2 Kyushu Univ., Japan</p>
<p>27P-11-151L Lamé-Mode Octagonal MEMS Resonator Utilizing Sliding Driving Electrodes T. Okamoto 1, H. Tanigawa 2 and K. Suzuki 1, 1 Ritsumeikan Univ, Japan</p>		